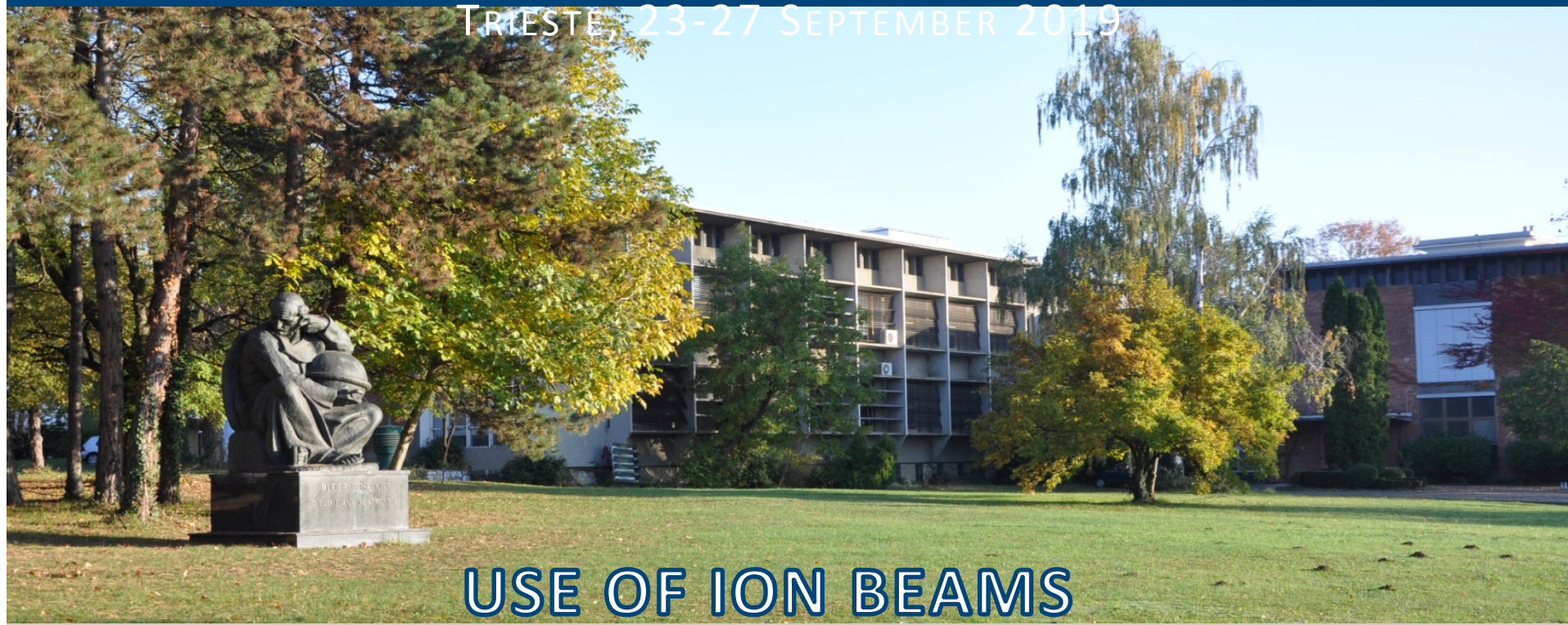


JOINT ICTP-IAEA INTERNATIONAL SCHOOL ON NUCLEAR WASTE VITRIFICATION

TRIESTE, 23-27 SEPTEMBER 2019



USE OF ION BEAMS FOR RADIATION DAMAGE AND ANALYSIS



*MARKO KARLUŠIĆ
RUĐER BOŠKOVIĆ INSTITUTE
ZAGREB, CROATIA*





MILKO JAKŠIĆ
ZDRAVKO SIKETIĆ
STJEPKO FAZINIĆ
IVA BOGDANOVIĆ-
RADOVIĆ
KRISTINA TOMIĆ
DAMJAN IVEKOVIĆ
ANDREJA GAJOVIĆ



HELSINGFORS UNIVERSITET
FLYURA DJURABEKOVA
HENRIQUE VÁZQUEZ



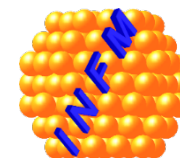
MARIKA SCHLEBERGER
OLIVER OCHEDOWSKI
LUKAS MADAUSS
LARA BRÖCKERS
ROLAND KOZUBEK



JACQUES O'CONNELL



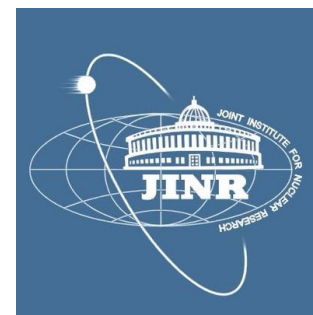
HENNING LEBIUS
BRIGITTE BAN-D' ETAT
ABDENACER BENYAGOUR



CORNELIU GHICA
RALUCA F. NEGREA



RENÉ HELLER
RICHARD A. WILHELM



VLADIMIR A. SKURATOV
RUSLAN RYMZHANOV

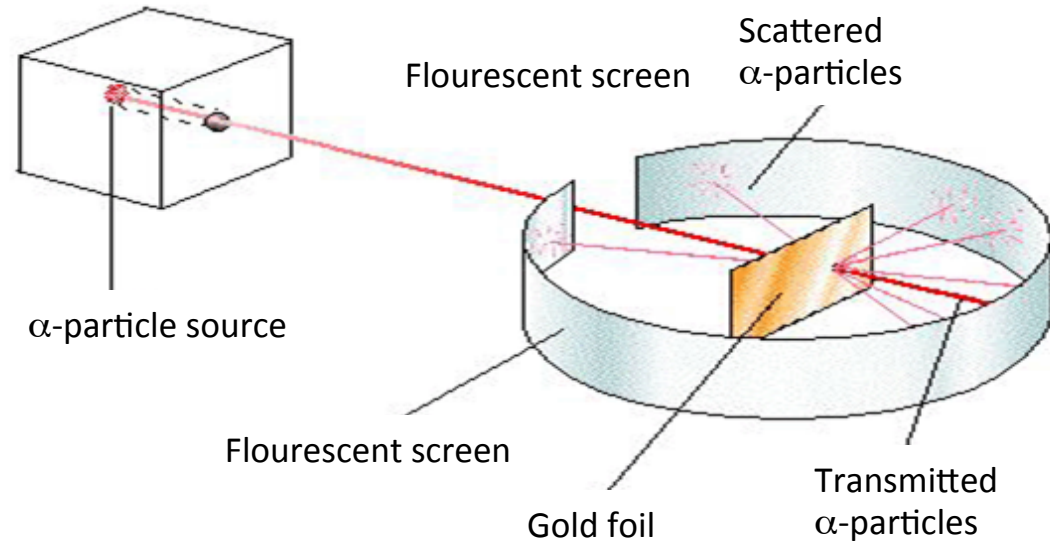
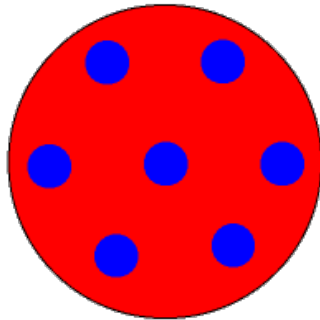


Overview

1. Introduction to IBA
2. RBS/channeling for ion tracks
3. RBS/c @ RBI

The first ion beam analysis: Rutherford experiment

Plum Pudding Model
of Atomic Structure



ERNEST RUTHERFORD

- 1909 – α -particle scattering experiment on gold foil
- 1911 – theory of nuclear atom

ION BEAM ANALYSIS (IBA) =
material analysis using (MeV) ion beams

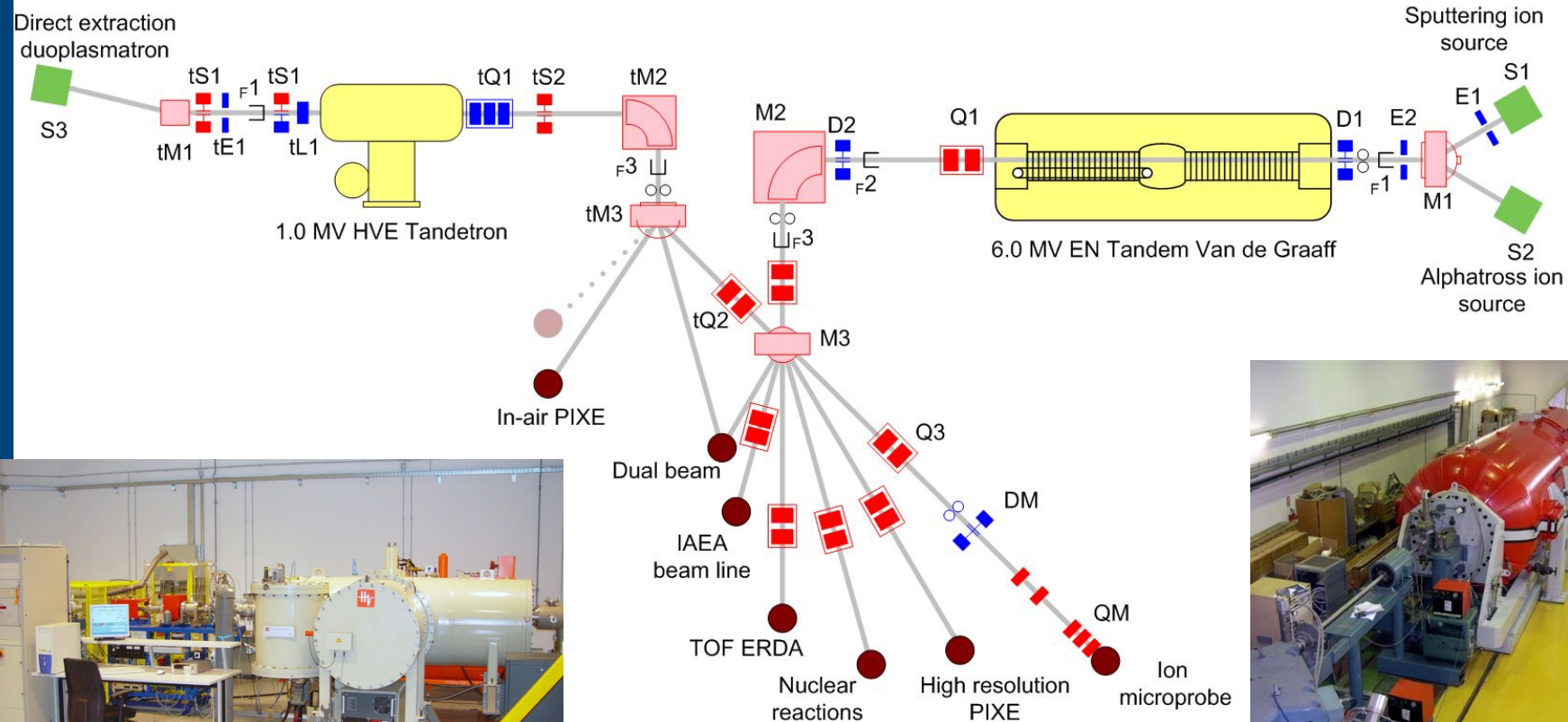
Accelerators today



Aprox. 20.000 accelerators:

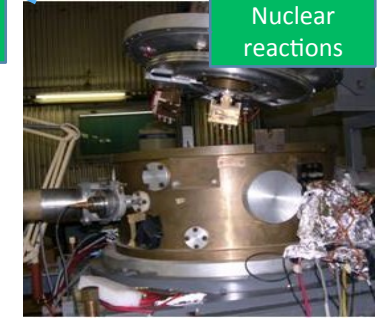
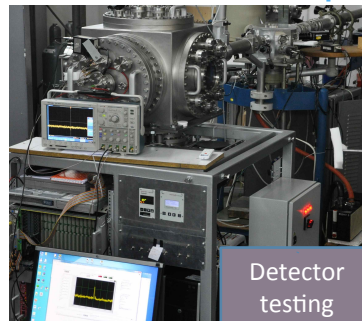
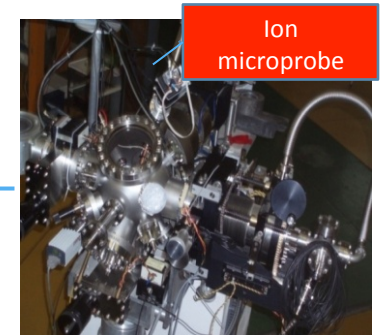
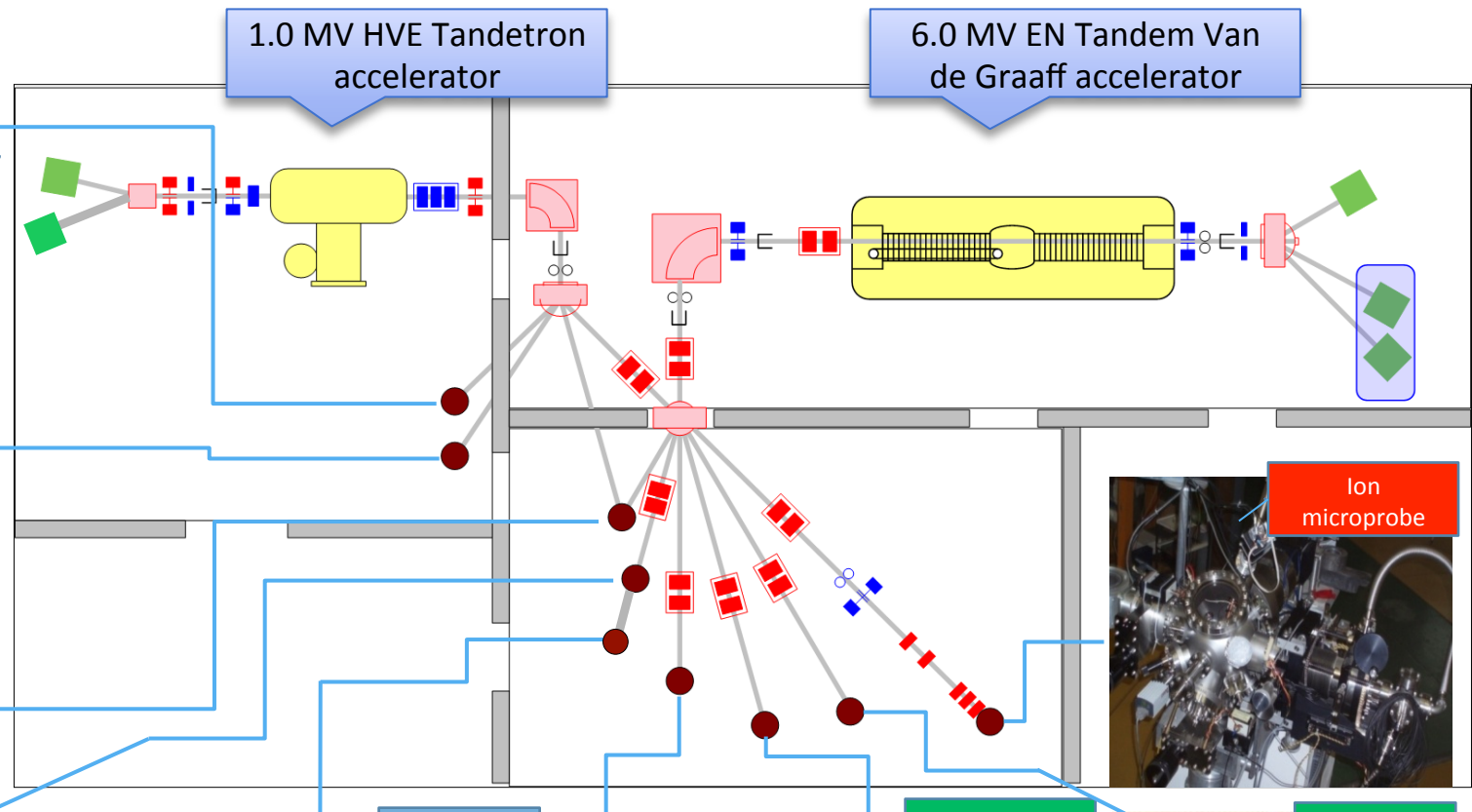
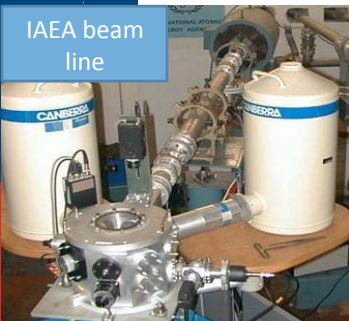
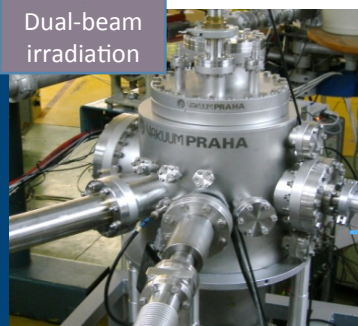
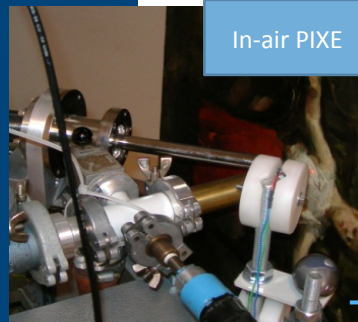
- 90% medicine & industry
 - Medicine
 - Diagnostics (isotope production)
 - Radiation treatment
 - Industry
 - Ion implanters
 - Electron accelerators for radiation processing (e.g. polimer crosslinking, sterilisation...)
- 10% research and education
 - Large scale facilities (e.g.CERN, GSI, etc.)
 - Synchrotron light sources
 - Cyclotrons
 - Electrostatic accelerators (including implanters)

RBI accelerator facility (RBI-AF)

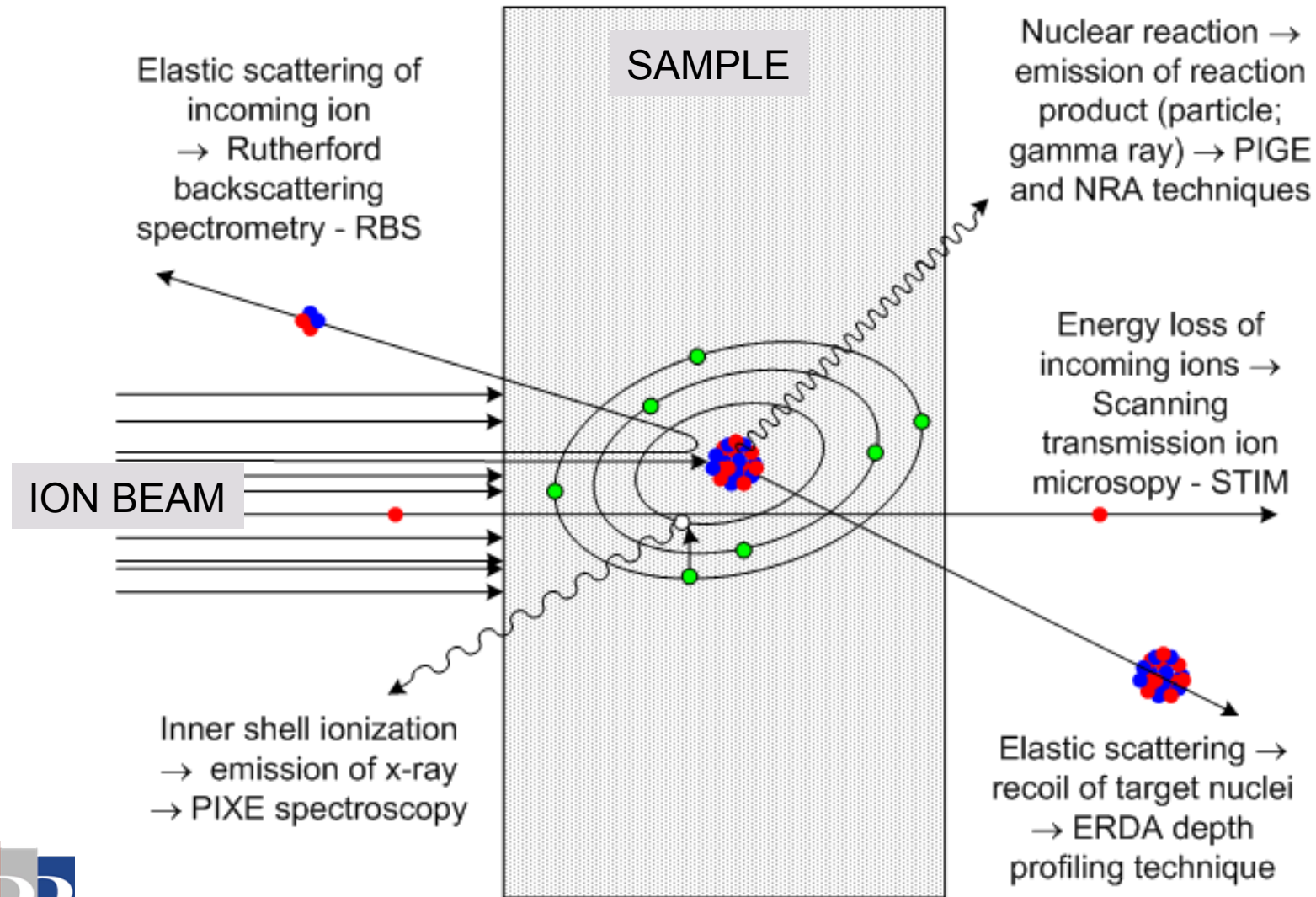


2 MeV p, 2 MeV He, 8 MeV C, 3 MeV O, 15 MeV O,
6 MeV Si, 15 MeV Si, 20+ MeV Cl, I, Au

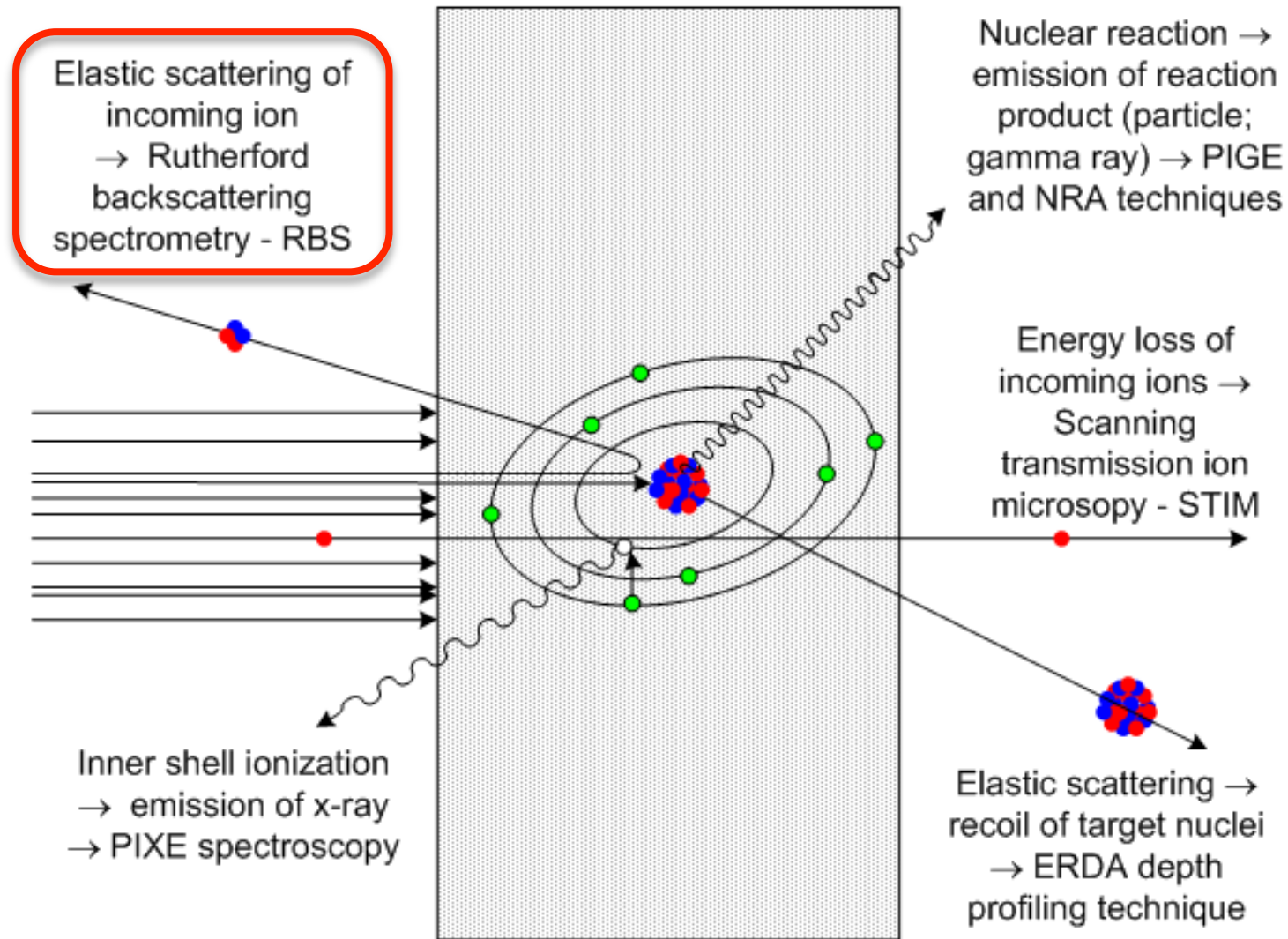
RBI accelerator facility (RBI-AF)



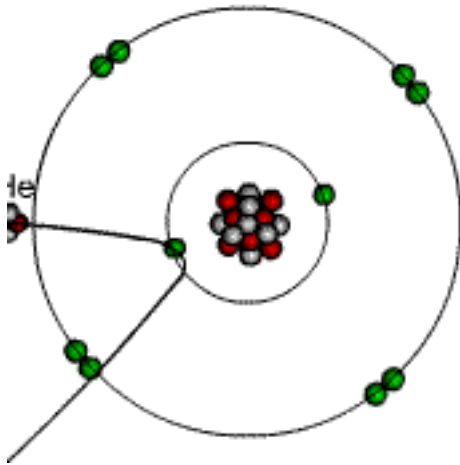
Ion beam analysis (IBA) techniques



Rutherford Backscattering Spectrometry (RBS)



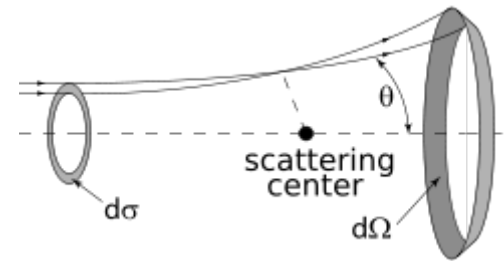
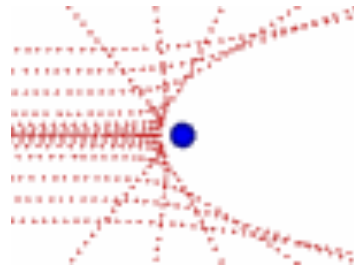
Rutherford Backscattering Spectrometry (RBS)



$$K = \frac{E_{\text{scattered}}}{E_{\text{incident}}} = \left[\frac{\left(1 - \left(\frac{M_1 \sin \theta}{M_2} \right)^2 \right)^{1/2} + \frac{M_1 \cos \theta}{M_2}}{1 + \frac{M_1}{M_2}} \right]^2$$

For a given scattering angle Θ , known projectile energy $E_{\text{inc.}}$ and mass M_1 (eg. 2 MeV α), $E_{\text{sc.}}$ can be measured and therefore unknown mass M_2 can be determined

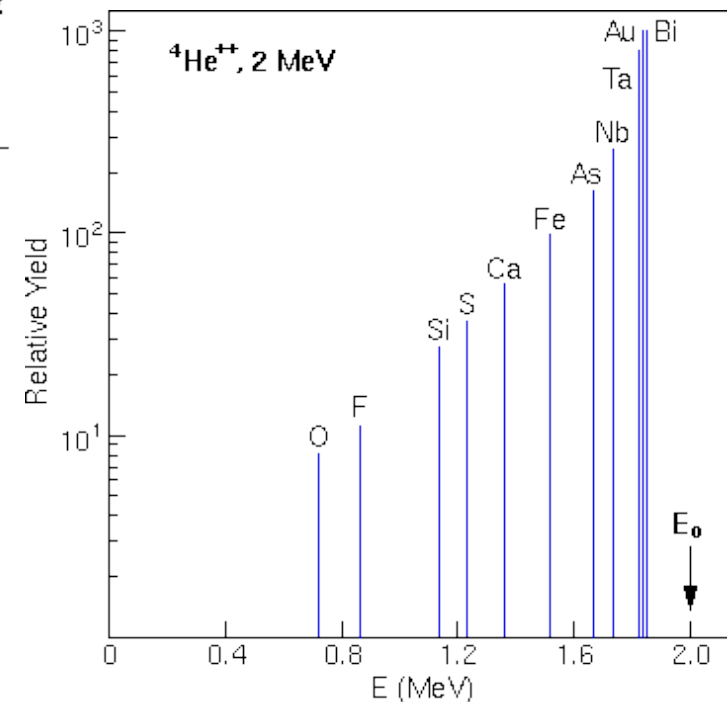
Rutherford Backscattering Spectrometry (RBS)



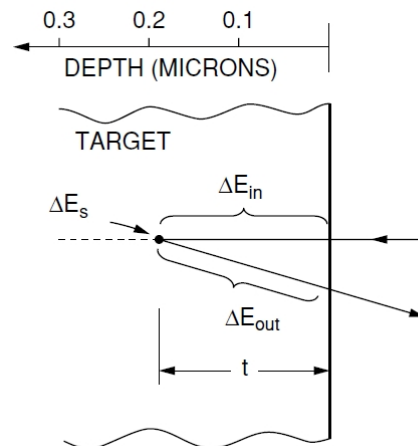
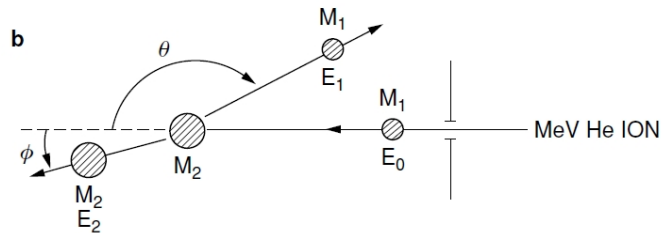
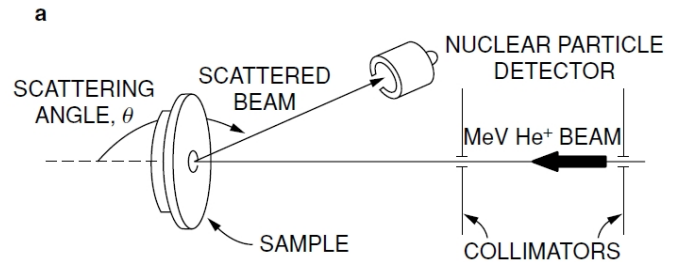
Cross section

$$\frac{d\sigma}{d\Omega} = \left[\frac{Z_1 Z_2 e^2}{4E} \right]^2 \cdot \frac{4}{\sin^4 \theta} \cdot \left[\frac{\sqrt{1 - \left[\frac{M_1 \sin \theta}{M_2} \right]^2} + \cos \theta}{\sqrt{1 - \left[\frac{M_1 \sin \theta}{M_2} \right]^2}} \right]^2$$

Z_1 Atomic number of incident ion
 Z_2 Atomic number of target atom
 E Energy of incident ion
 M_1 Mass of incident ion
 M_2 Mass of target atom
 θ Angle of incidence



Rutherford Backscattering Spectrometry (RBS)



$$\Delta E_{in} = \left. \frac{dE}{dx} \right|_{E_0} \cdot t$$

$$E_t = E_0 - \Delta E_{in}$$

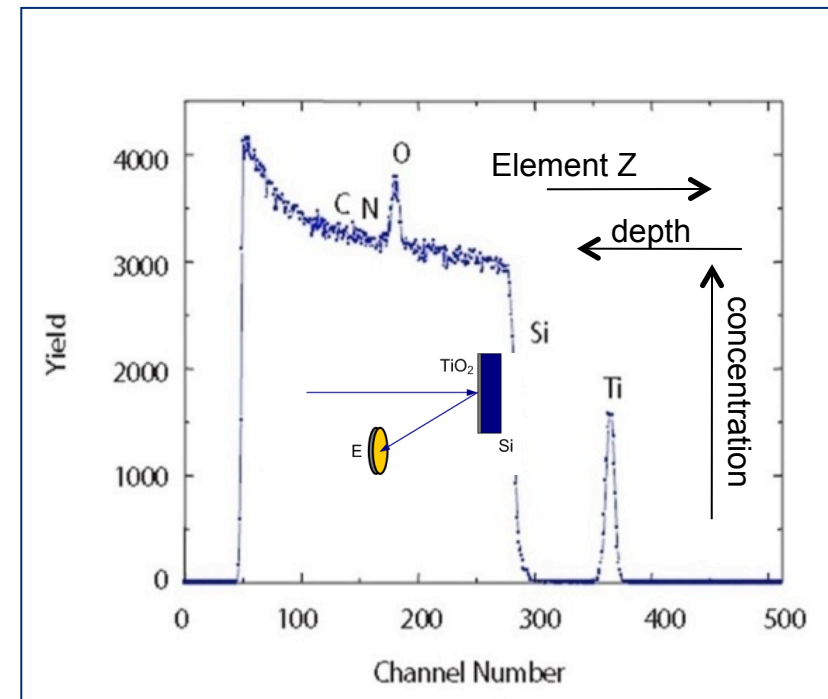
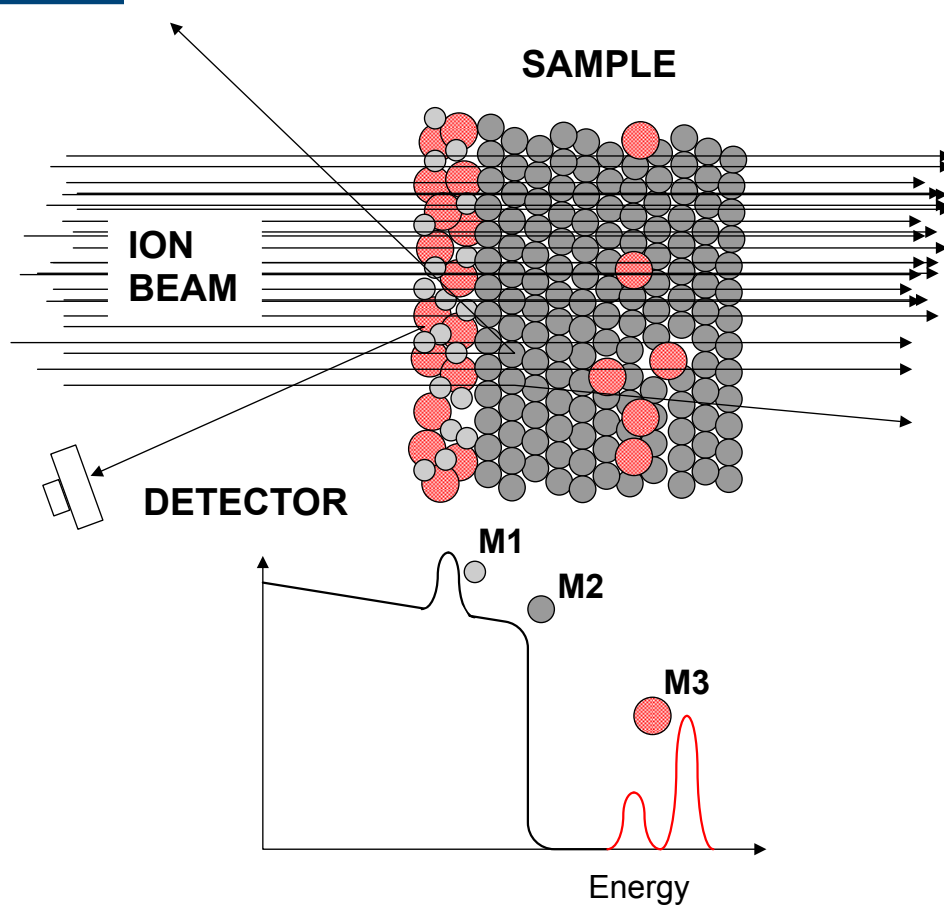
$$\Delta E_s = (1 - K) E_t$$

$$\Delta E_{out} = \left. \frac{dE}{dx} \right|_{E_1} \cdot \frac{t}{\cos \theta}$$

$$K = \frac{E_1}{E_0} = \left[\frac{(M_2^2 - M_1^2 \sin^2 \theta)^{1/2} + M_1 \cos \theta}{M_1 + M_2} \right]^2$$

Rutherford Backscattering Spectrometry (RBS)

Depth profiling



Proton beam (2 MeV)
Detector positioned at $\Theta=165^\circ$

Sample: thin TiO₂ film on Si
substrate

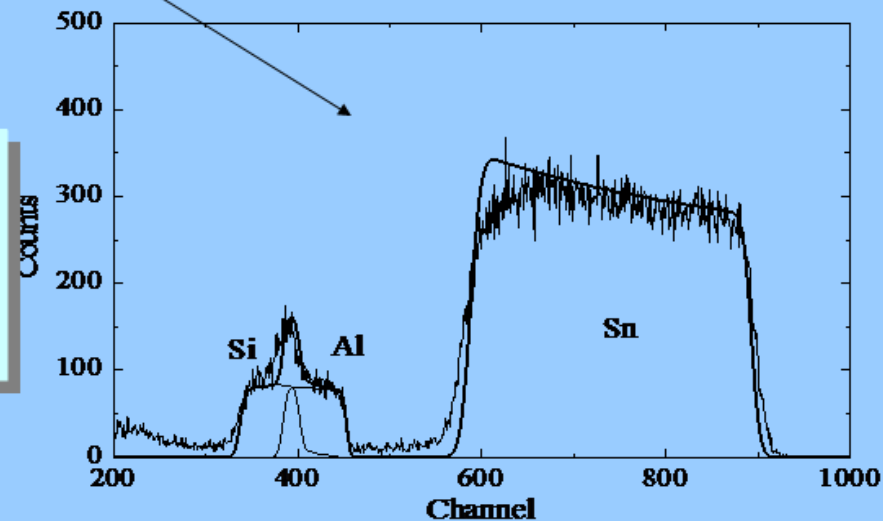
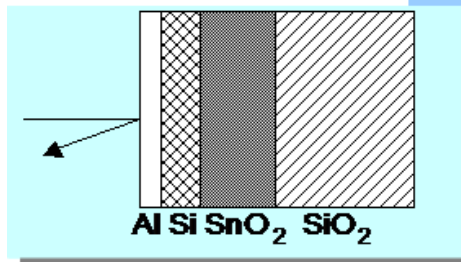
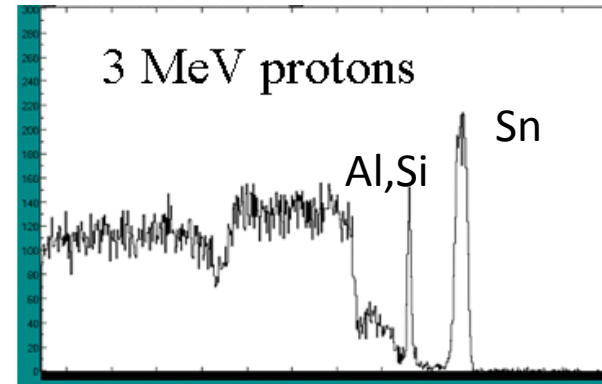
Rutherford Backscattering Spectrometry (RBS)

Depth profiling

Sample:
thin film a-Si solar cell
(amorphous silicon)

5.1 MeV Li^{2+} beam

$\Theta = 170^\circ$



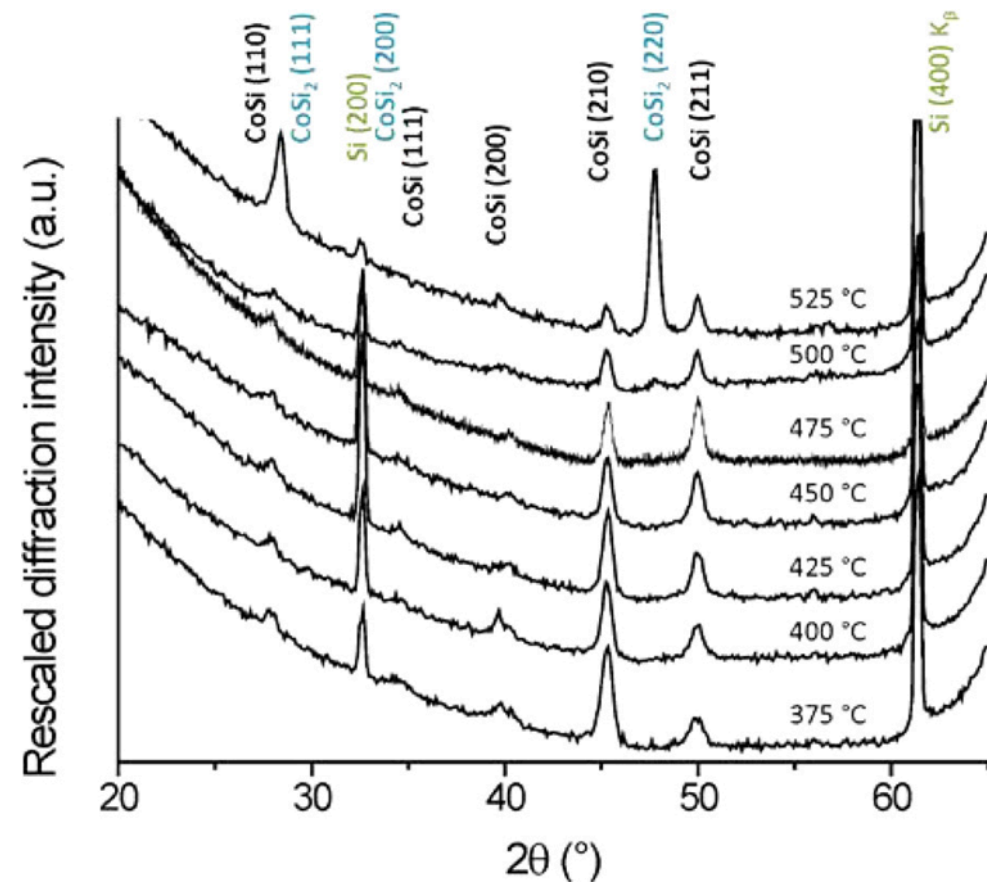
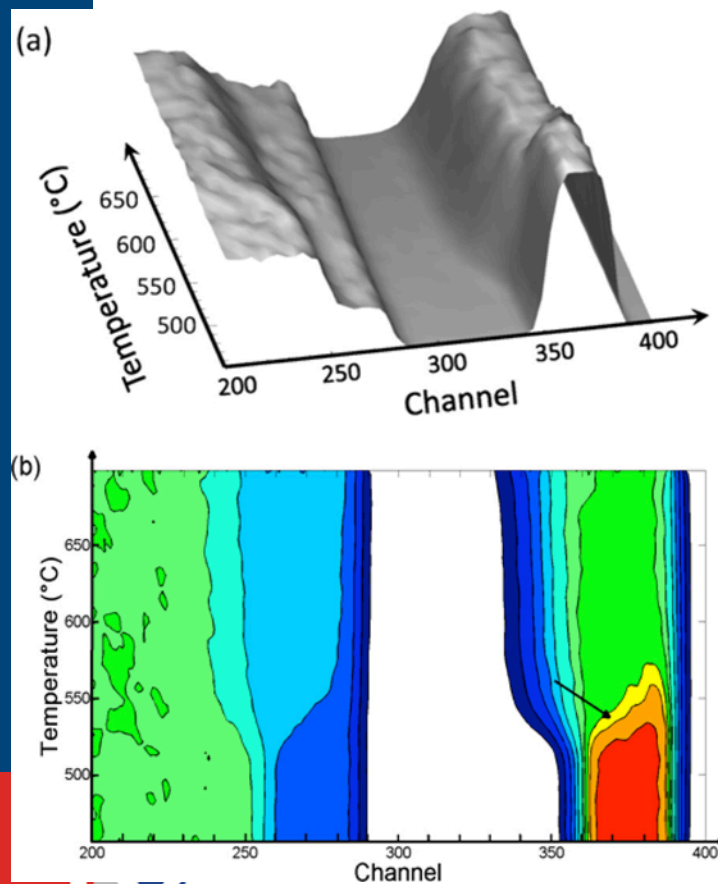
Rutherford Backscattering Spectrometry (RBS)

In situ analysis

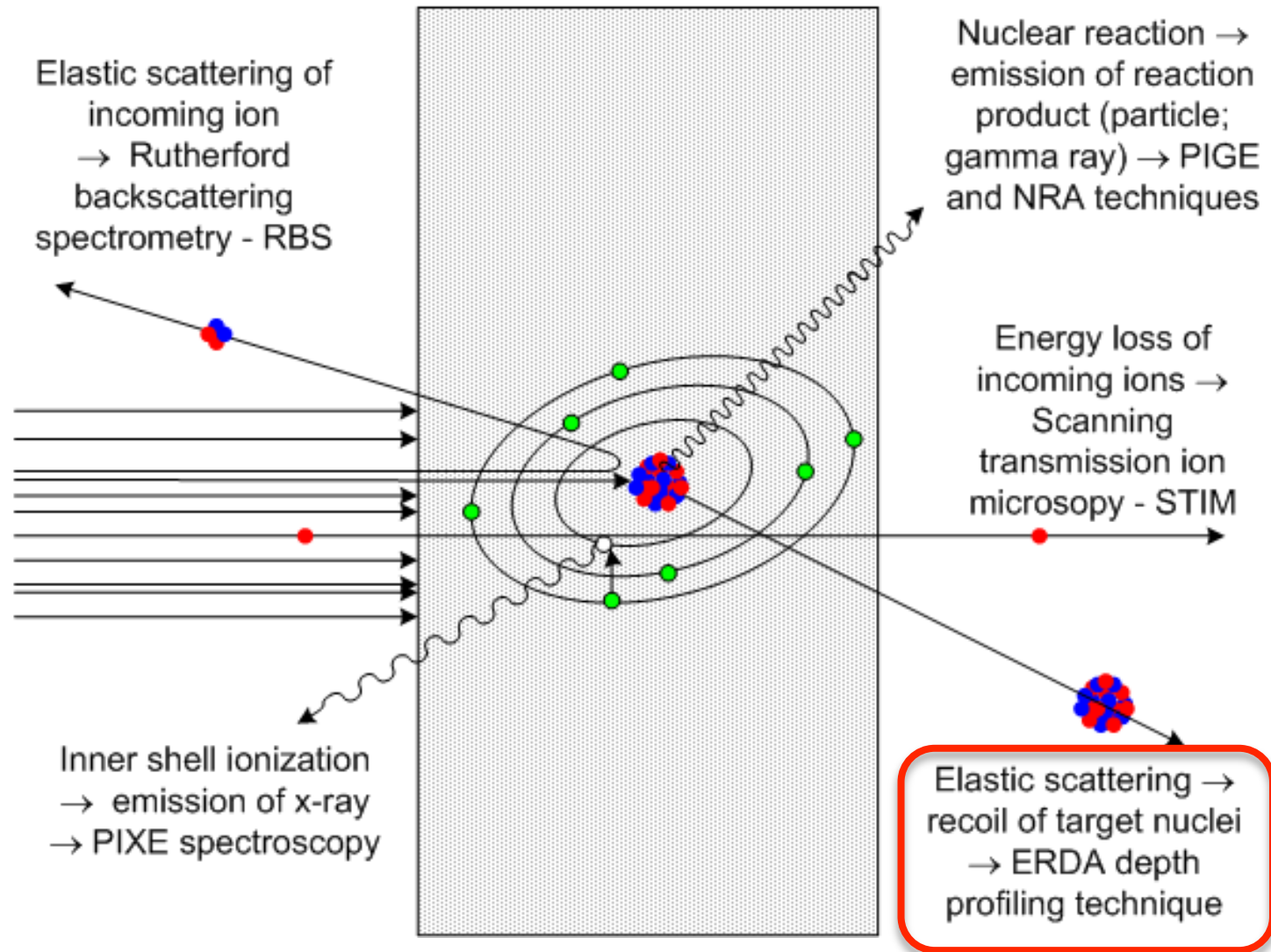
Effect of high temperature deposition on CoSi₂ phase formation

C. M. Comrie, et al. J. Appl. Phys. 113 (2013)

- Identification of phase transition from CoSi to CoSi₂



Elastic Recoil Detection Analysis (ERDA)



Elastic Recoil Detection Analysis (ERDA)

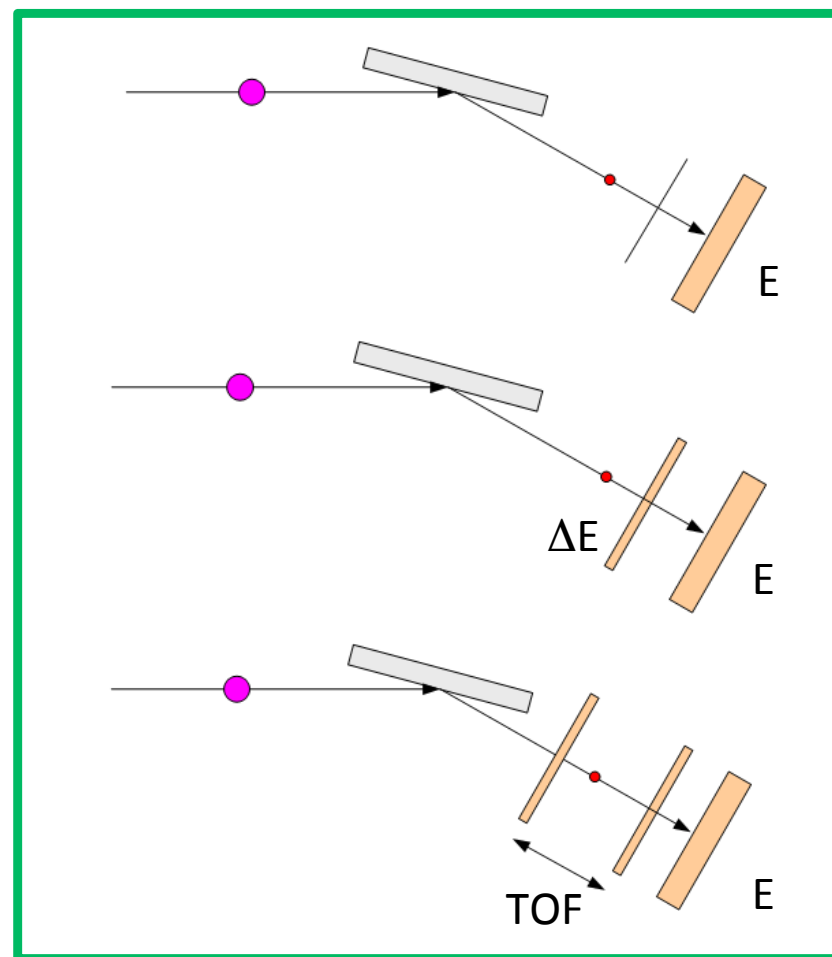
Experimental setup:

Stopping foil – by selection of appropriate thickness, system is optimized for one particular element (e.g. Hydrogen using He ion beam)

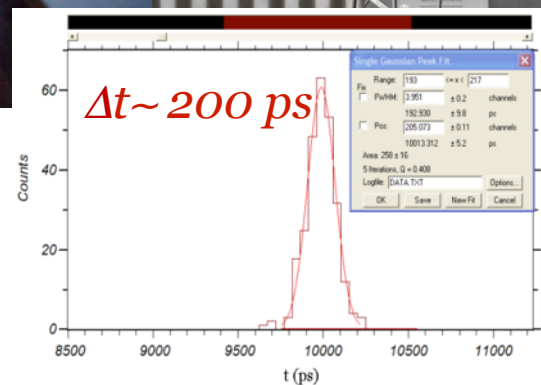
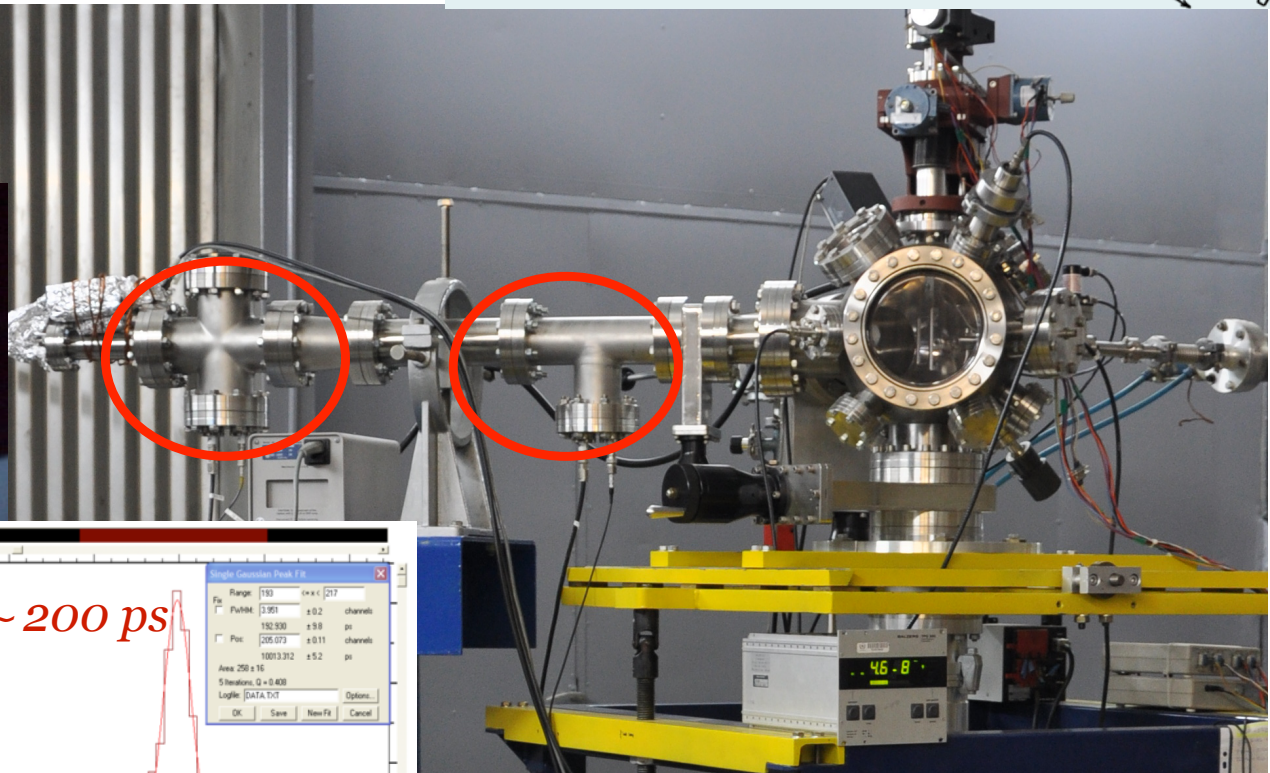
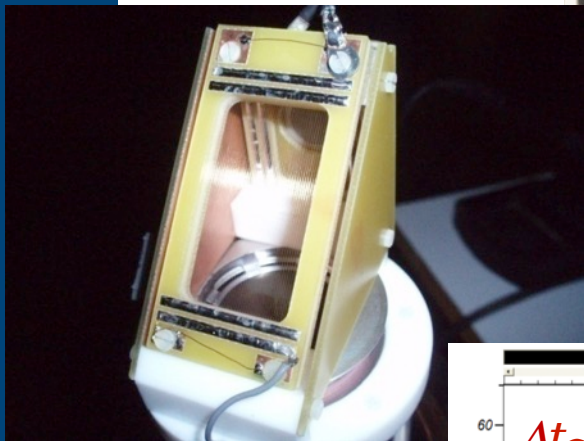
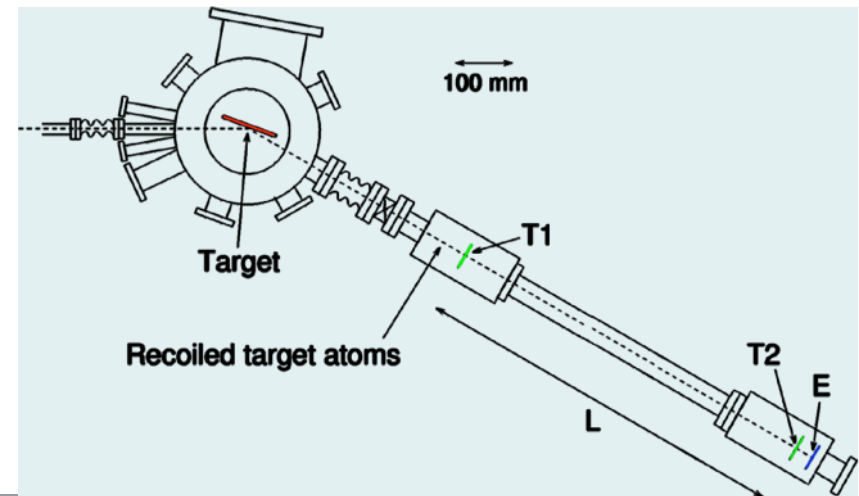
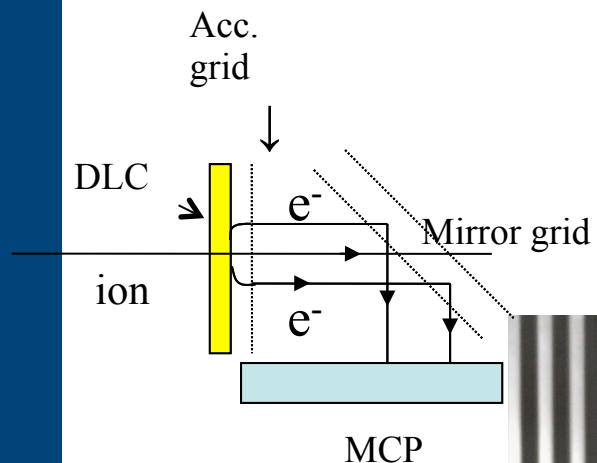
ΔE , E detector: - scattered and recoiled particles are discriminated by different dE/dx ! (energy straggling ?)

TOF, E detector:
- scattered and recoiled particles are discriminated by measurement of time of flight (with minimal straggling) – best depth resolution

+ Magnetic spectrometer (expensive)



ToF – ERDA @ RBI-AF

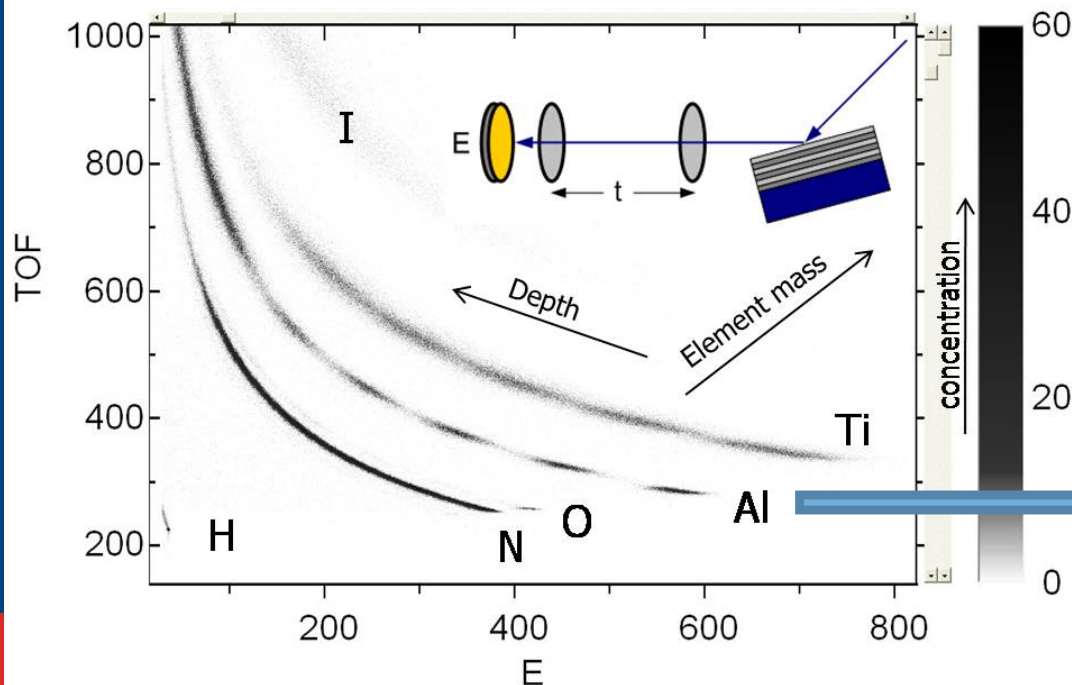


Z. Siketić, PhD thesis (2010)

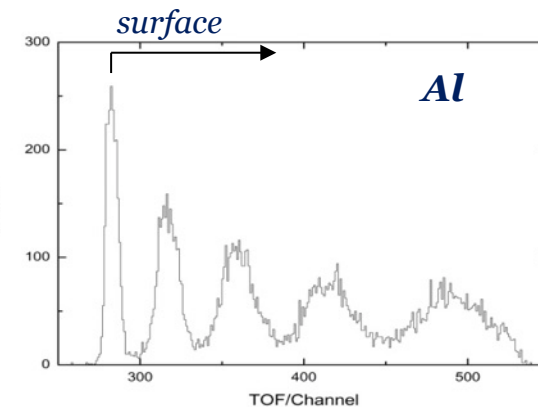
ToF – ERDA @ RBI-AF

Heavy ion beam – e.g. 20 MeV Iodine ions

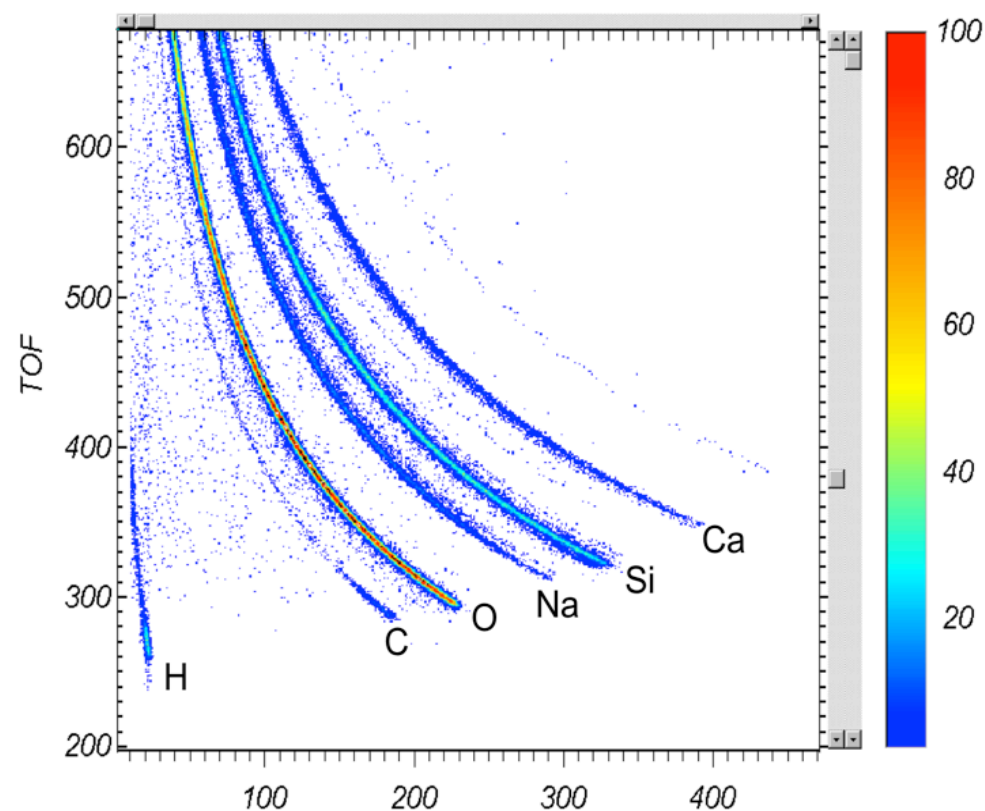
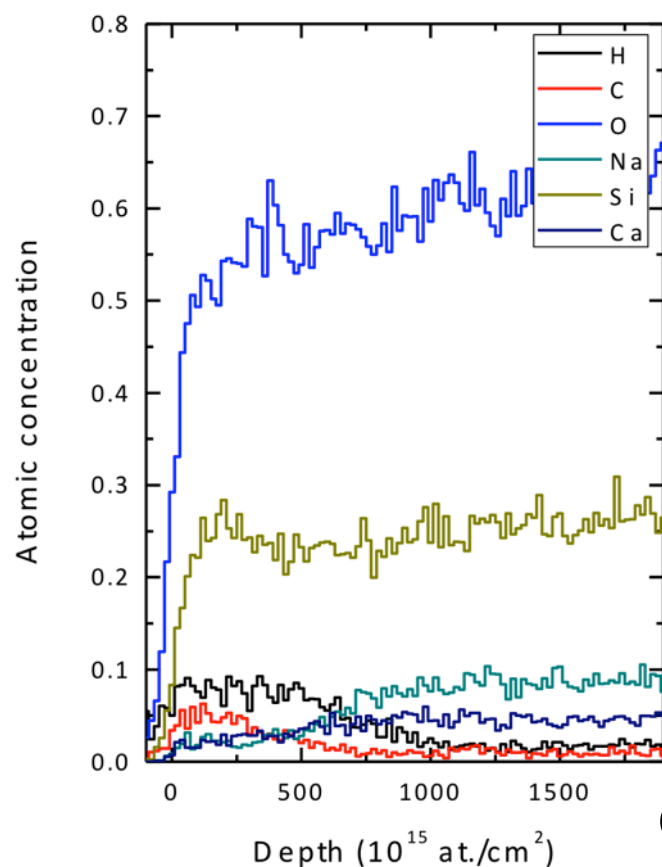
- sensitivity 10^{15} /cm²
- 5 nm depth resolution, up to 500 nm probe depth
- all elements are resolved simultaneously



Sample:
20 nm multilayers TiN/AlN



ToF – ERDA @ RBI-AF



Corrosion of ancient glass found at the fort Sokol
(close to Dubrovnik airport)

Other IBA techniques... important for us ?

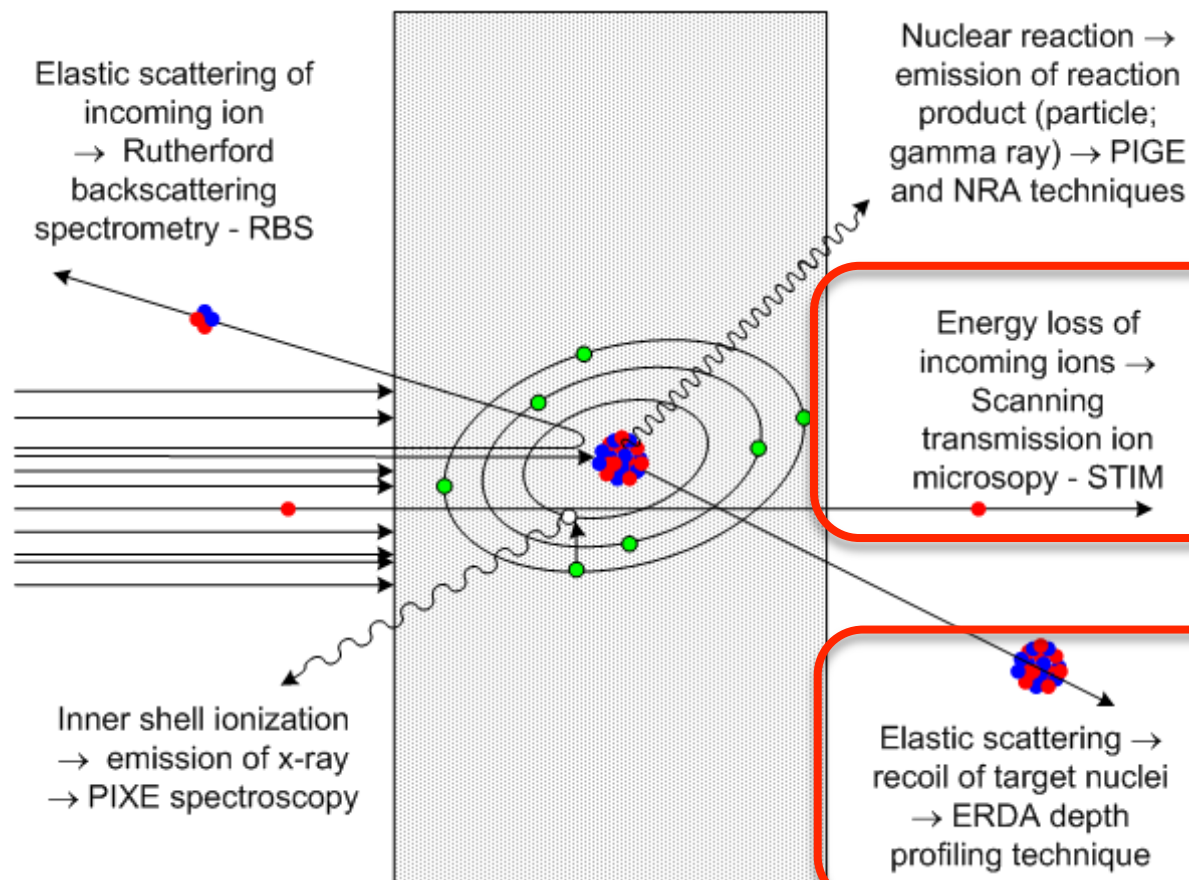
RBS in
channeling
(RBS/c)

Secondary
electrons
SE imaging

Ionolumi-
nescence (IL)

High
resolution
HR-PIXE

Elastic scattering of
incoming ion
→ Rutherford
backscattering
spectrometry - RBS



Inner shell ionization
→ emission of x-ray
→ PIXE spectroscopy

Nuclear reaction →
emission of reaction
product (particle;
gamma ray) → PIGE
and NRA techniques

Energy loss of
incoming ions →
Scanning
transmission ion
microscopy - STIM

Elastic scattering →
recoil of target nuclei
→ ERDA depth
profiling technique

MeV-SIMS

Ion beam
induced
charge
(IBIC)

P-p & C-C
scattering

Resources - books

Y. Wang, M. Nastasi, *Handbook of Modern Ion Beam Materials Analysis* (MRS 2009)

W.K. Chu, W.J. Mayer, M.A. Nicolet, *Backscattering Spectrometry* (AP 1978)

LC Feldman, JW Mayer, ST Picraux:
Materials Analysis by Ion Channeling (Elsevier 1982)

W.R. Leo, *Techniques for Nuclear and Particle Physics Experiments: a How-to Approach* (Springer 1987)

Overview

1. Introduction to IBA
2. RBS/channeling for ion tracks
3. RBS/c @ RBI

MATERIALS MODIFICATIONS USING ION BEAMS

Ion implantation:

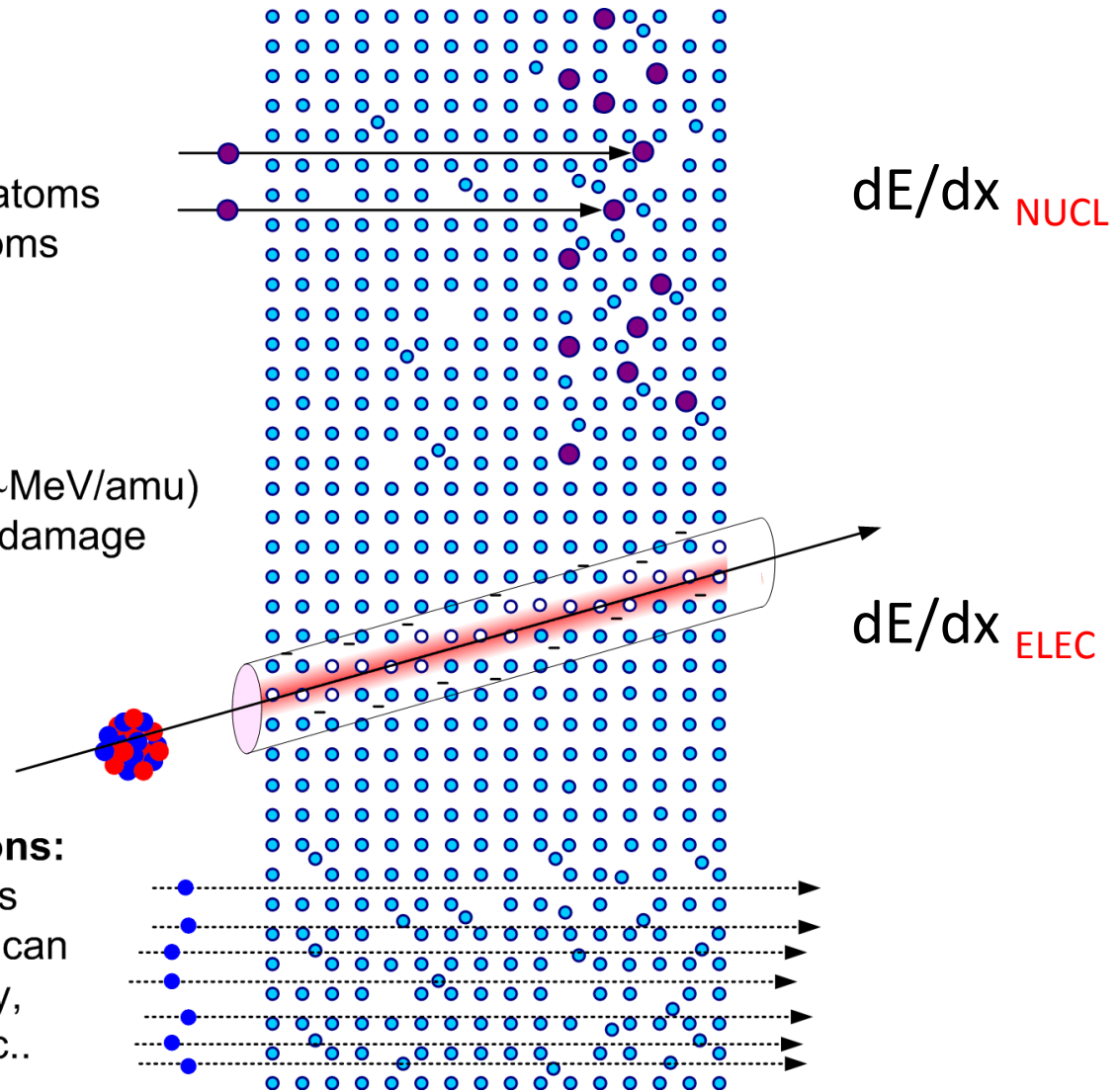
- a) Injection of foreign atoms
- b) Displacement of atoms

Single ion tracks:

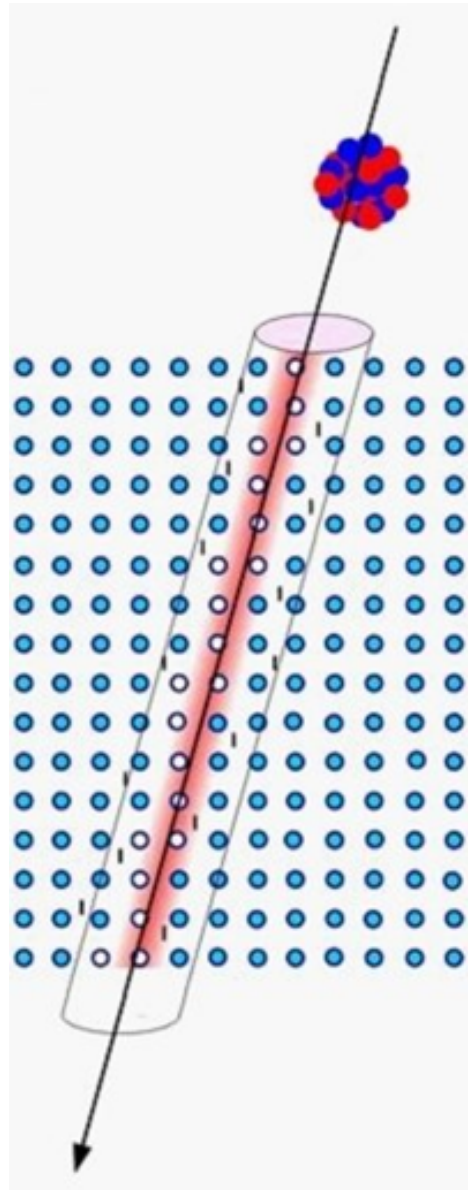
Fast and heavy ions ($\sim \text{MeV/amu}$) create latent tracks of damage used as a template in nanostructuring

Irradiation with protons:

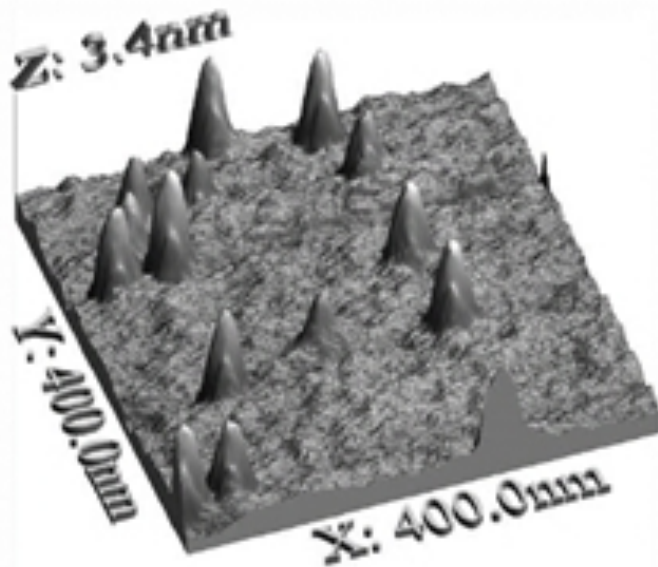
Produce homogeneous radiation damage that can be used for lithography, defect engineering, etc..



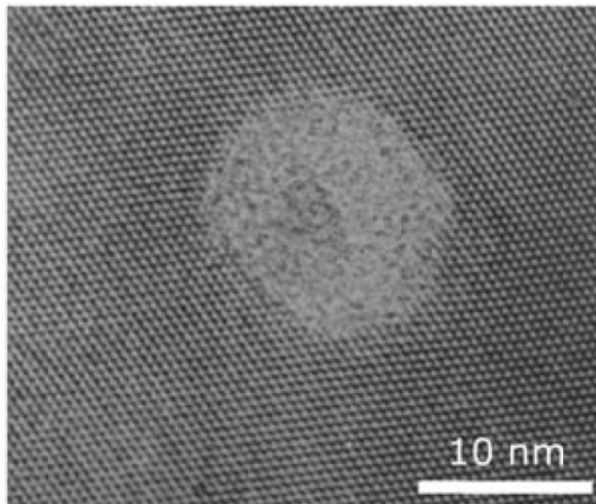
SWIFT HEAVY ION BEAMS FOR MATERIALS MODIFICATIONS



- SWIFT (>1 MeV/amu)
- HEAVY (>20 amu)
- ION TRACK: permanent damage after passage of SWIFT HEAVY ION
- THRESHOLD (melting): relevant is dE/dx_{ELEC} , not E !
- FISSION FRAGMENTS
- LARGE ACCELERATOR FACILITIES

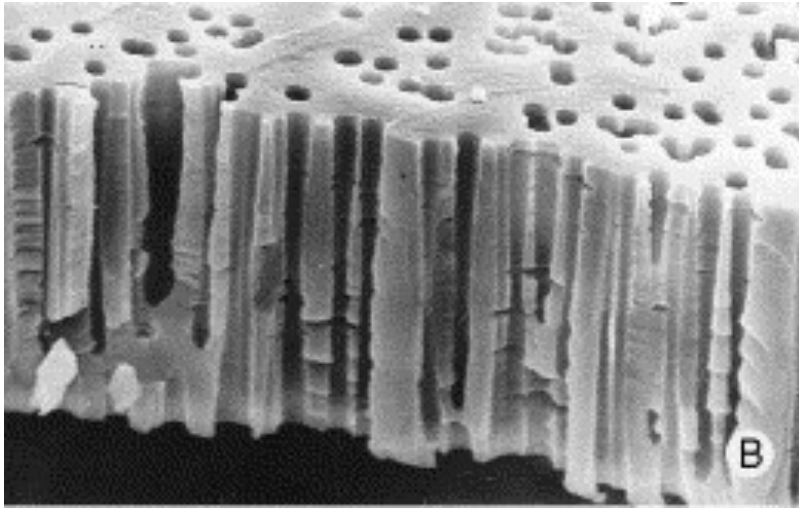


Zollondz (2004): 1 GeV U \Rightarrow DLC

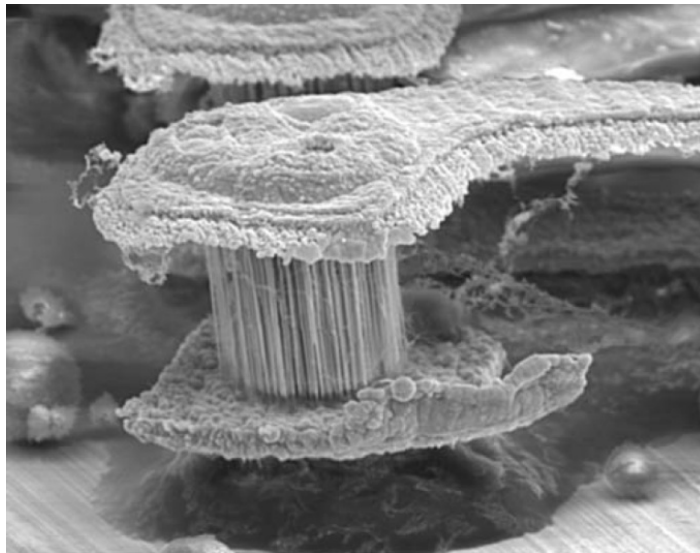


Vetter (1998):
2.4 GeV Pb \Rightarrow mica

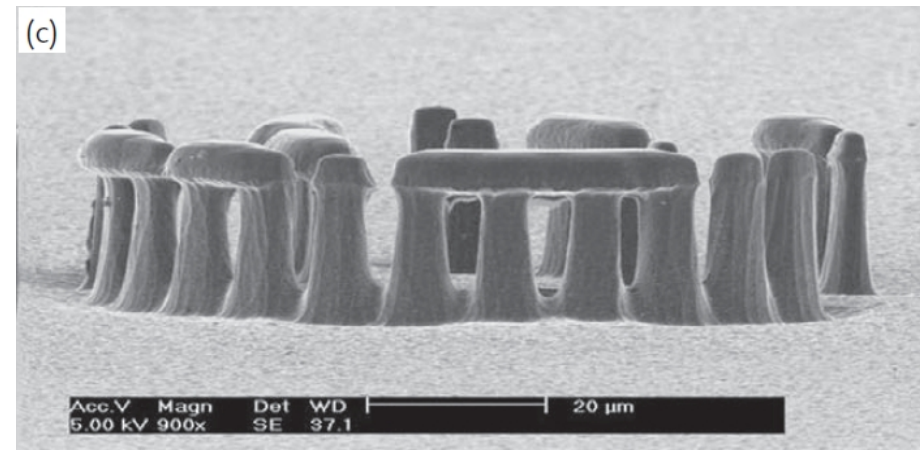
- SWIFT (>1 MeV/amu)
- HEAVY (>20 amu)
- ION TRACK: permanent damage after passage of SWIFT HEAVY ION
- THRESHOLD (melting): relevant is dE/dx_{ELEC} , not E !
- FISSION FRAGMENTS
- LARGE ACCELERATOR FACILITIES



P. Apel, NIMB 2003



*Lindenberg et al.,
Microsys. Techn. 2004*

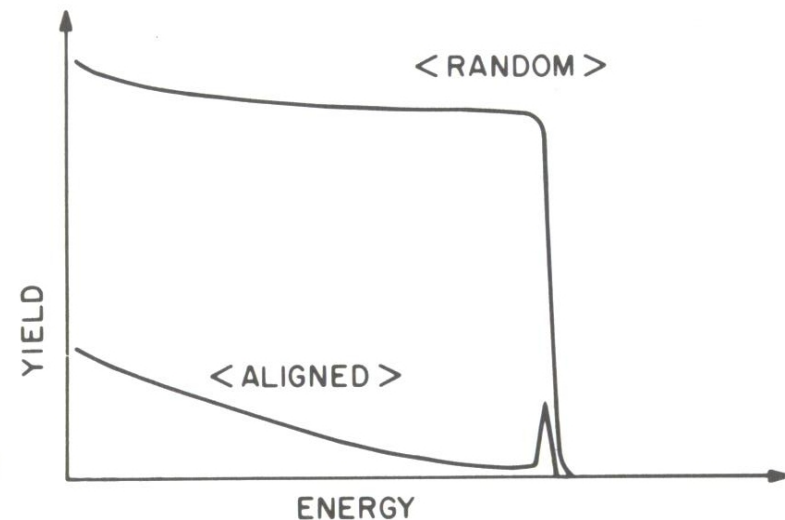
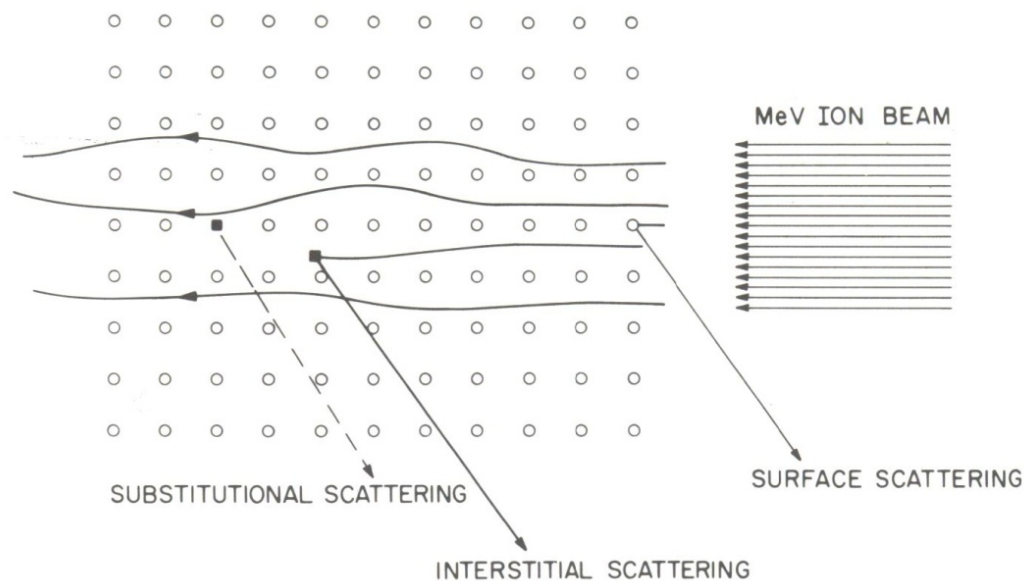


F. Watt et al., Mat. Today (2007)

Ion track analysis using RBS/channeling

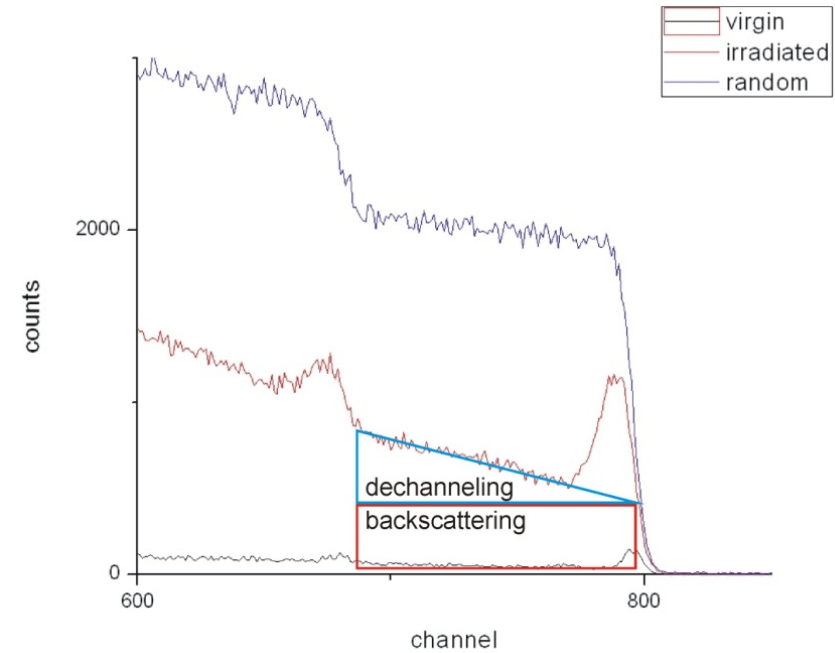
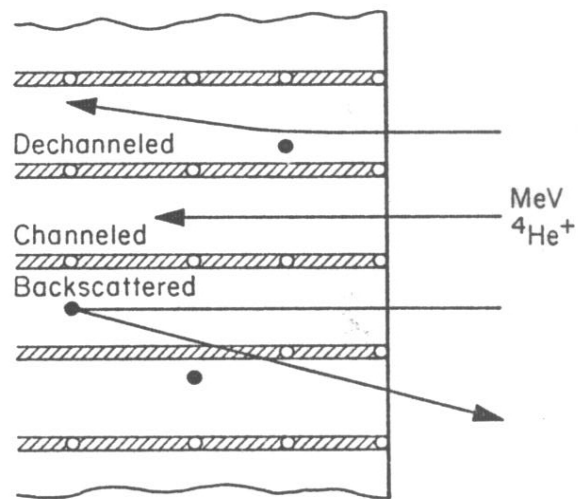
- Applicable for any type of damage (nuclear/electronic dE/dx)
- Possible to analyse greater number of samples than TEM
- Applicable for single crystal targets !

*LC Feldman, JW Mayer, ST Picraux:
Materials analysis by Ion Channeling (1982)*



Critical channeling angle:
$$\psi_c = \left(\frac{Z_1 Z_2 e^2}{Ed} \right)^{1/2}$$

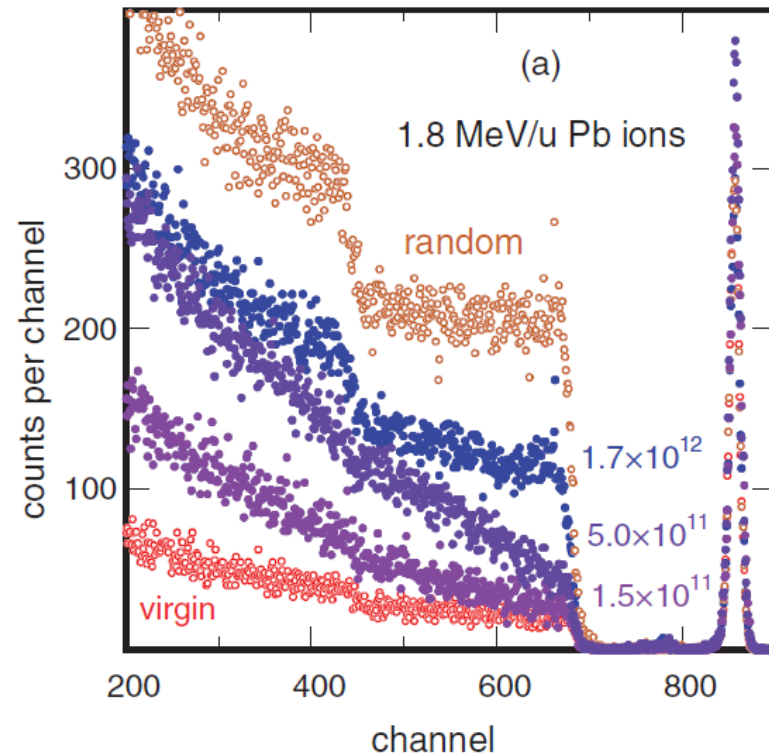
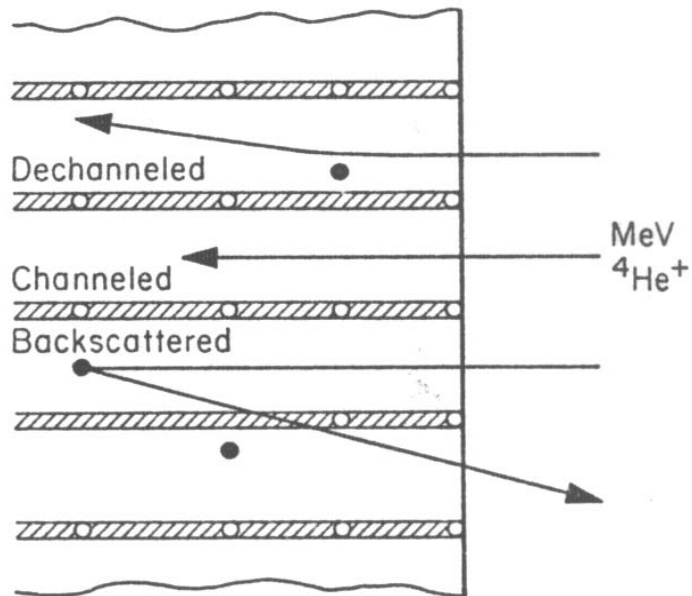
Ion track analysis using RBS/channeling



Surface approximation

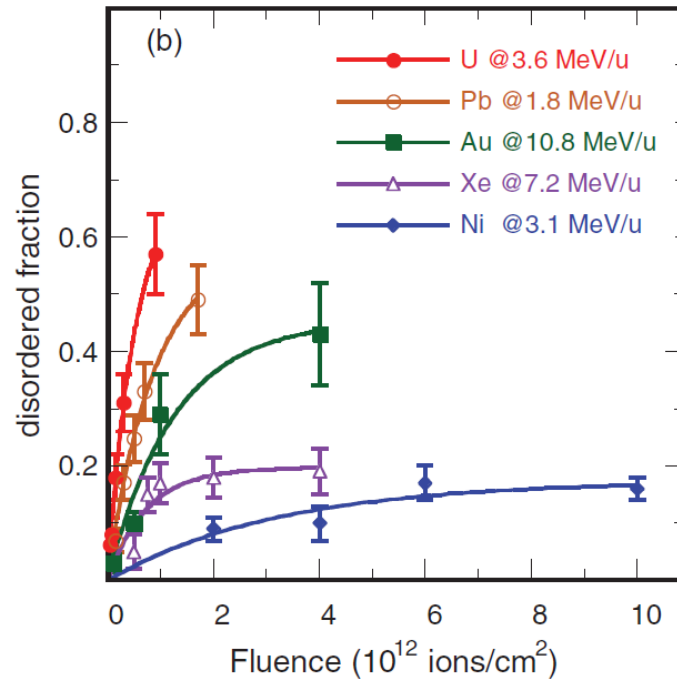
$$F_d = \frac{\chi_{irrad} - \chi_{virgin}}{\chi_{random} - \chi_{virgin}}$$

Ion track analysis using RBS/channeling



*Toulemonde et al.,
PRB (2012): CaF_2*

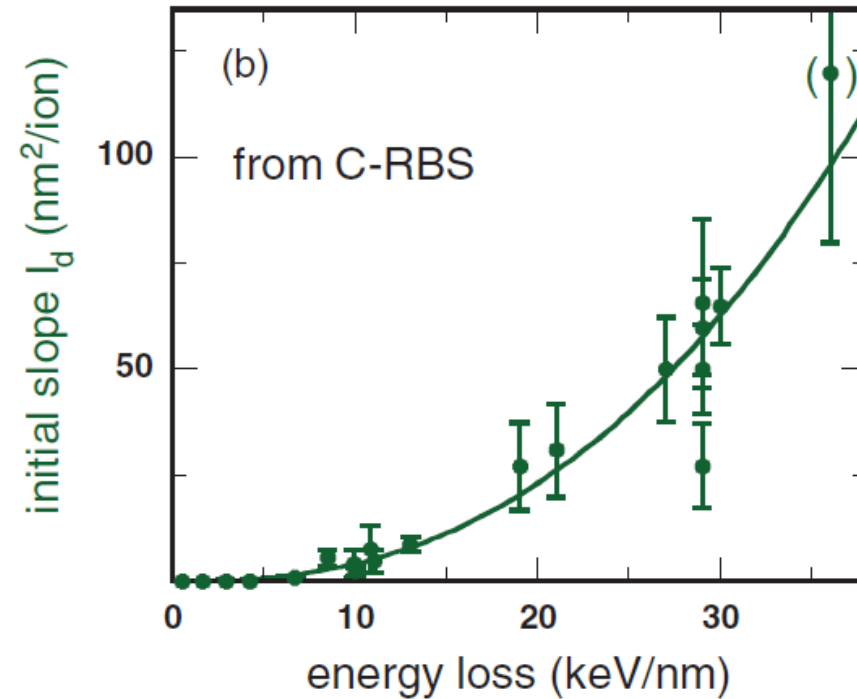
Ion track analysis using RBS/channeling



*Toulemonde et al.,
PRB (2012): CaF₂*

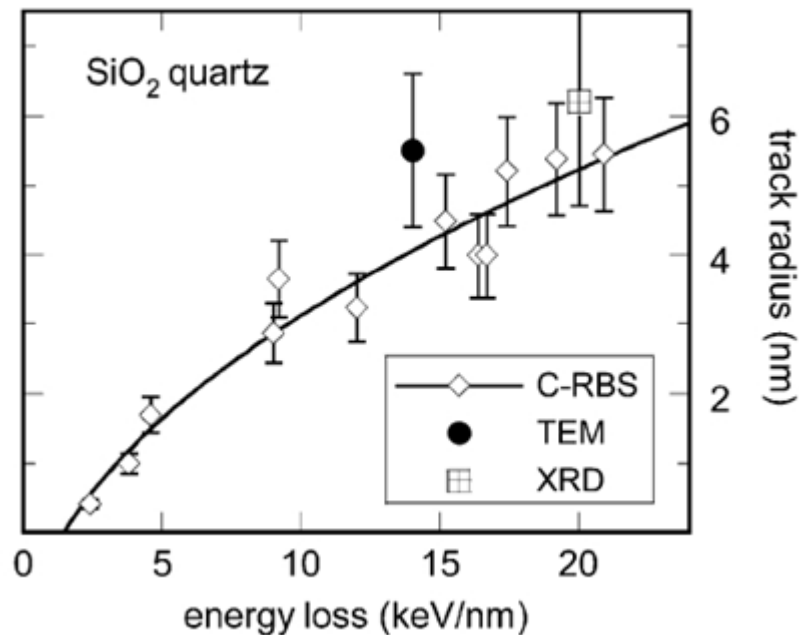
$$F_d = \alpha \left(1 - e^{-R^2 \pi \Phi} \right)$$

Poisson law



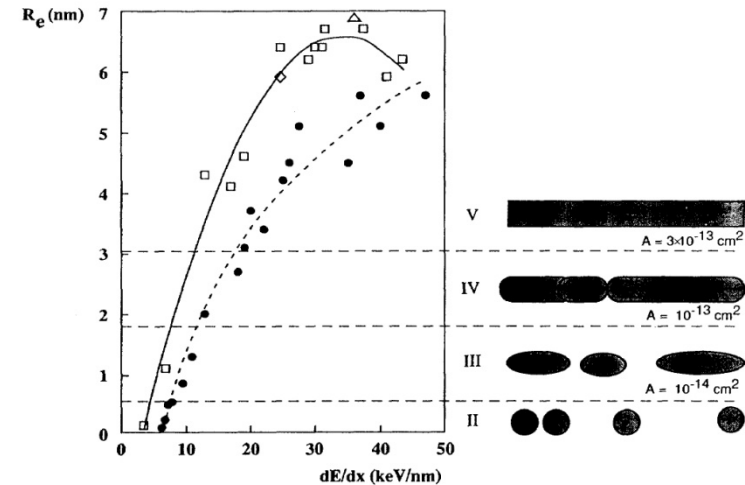
*For 1 data point,
~ 5 samples measured
with RBS/c*

Ion track analysis using RBS/channeling



Toulemonde MfM (2006)

*Overall good agreement
RBS/c with other techniques
(amorphizable materials)*



Meftah PRB (1993)

*But close to threshold ion
tracks are discontinuous*

*RBS/c measures effective ion
track cross section*

*Different but perhaps more
appropriate than TEM!*

Ion track analysis using RBS/channeling

Discontinuous tracks

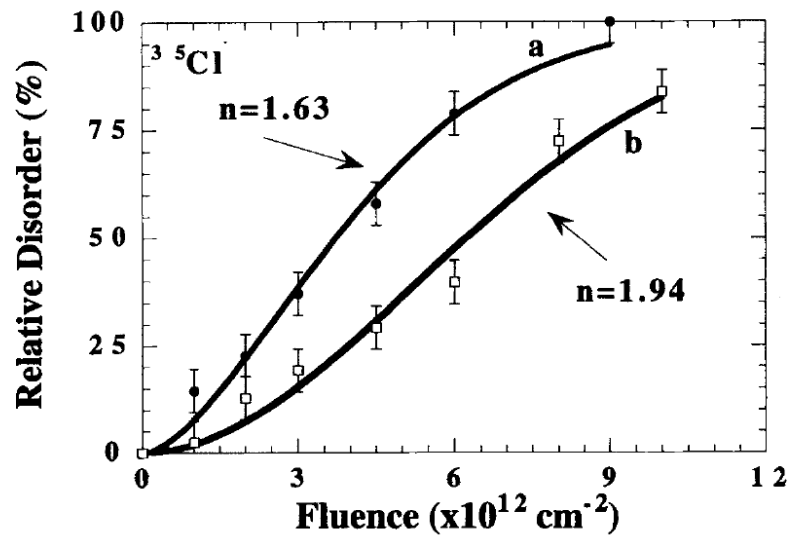


FIGURE 4 Relative disorder in LiNbO_3 versus the chlorine fluence. Irradiations performed at two different energies: 10 MeV (circles) and 7 MeV (squares). The continuous lines correspond to the best fits of experimental data by using the AVRAMI model (Eq. (4): $\alpha = 1 - \exp(-(\phi/\phi_c)^n)$). The ϕ_c values obtained for these two energies were 4.6×10^{12} and $7.5 \times 10^{12} \text{ cm}^{-2}$, respectively.

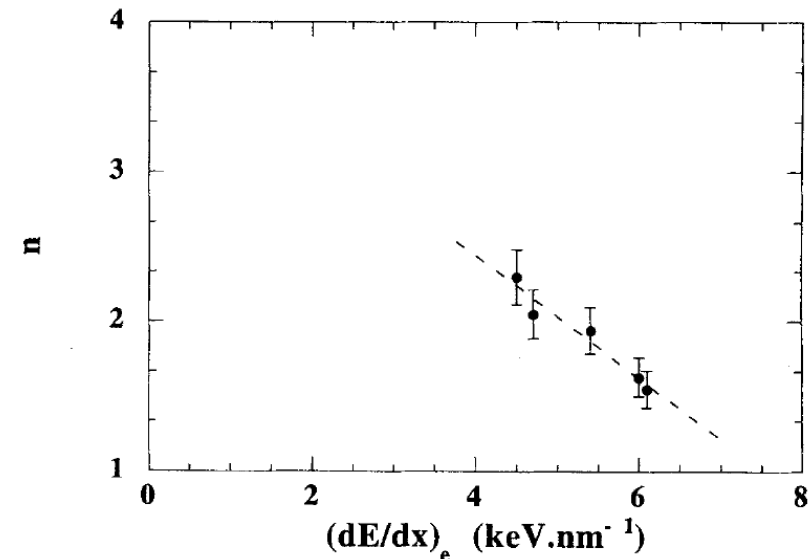


FIGURE 5 Evolution of the exponent n , fitted from Eq. (4), versus the electronic stopping power.

SMM Ramos et al., REDS (1998)

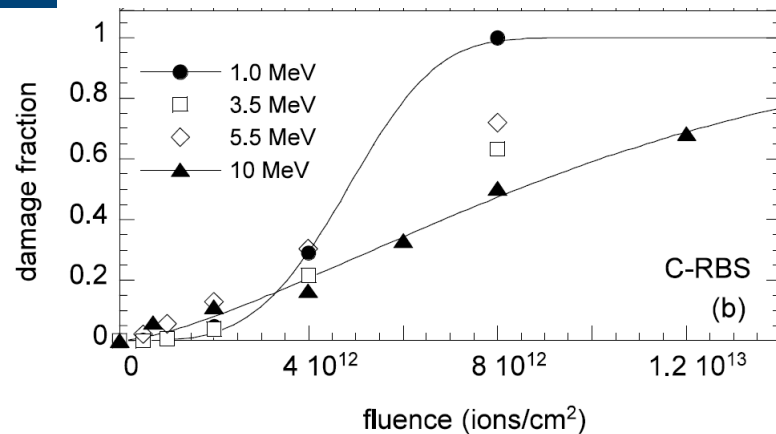
$$\alpha = 1 - \exp(-(\phi/\phi_c)^n)$$

Avrami equation: sigmoidal shape, incubation fluence

*For 1 data point,
5+ samples measured
with RBS/C*

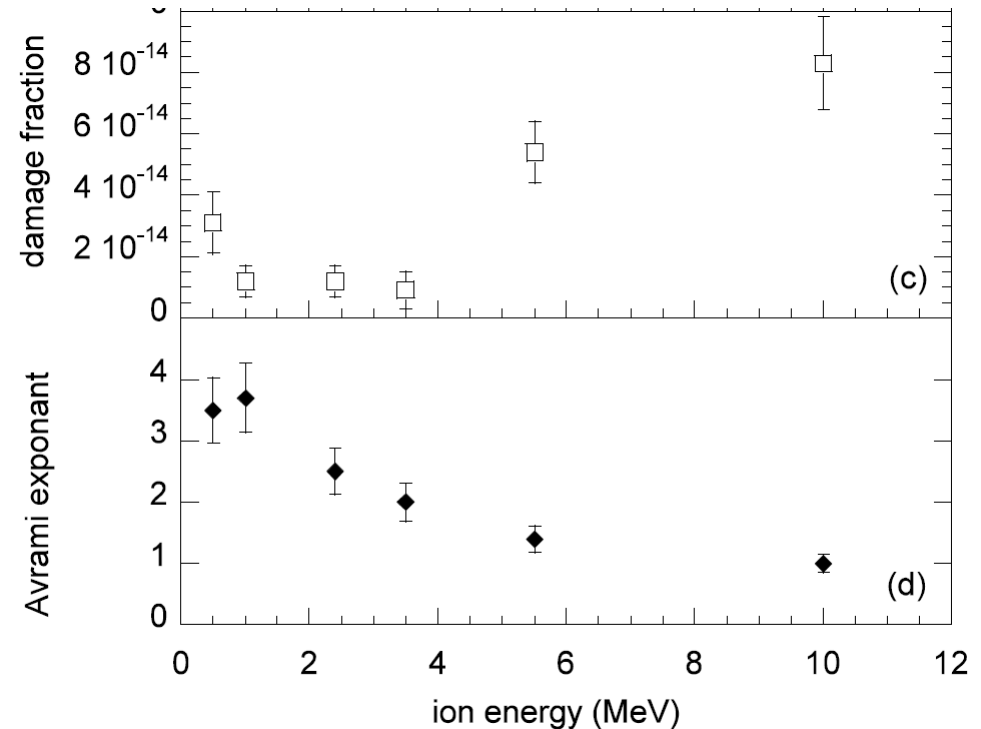
Ion track analysis using RBS/channeling

Nuclear stopping contribution



Au irradiation of SiO₂ quartz

Bernas et al., NIMB (2001)



*Avrami formalism is useful extension of the Poisson law,
but many measurements are necessary for 1 data point
In situ RBS/c is an excellent solution for saving beamtime!*

Ion track analysis using RBS/channeling

Nuclear stopping contribution

Table 1
Main irradiation parameters and some of the swelling and C-RBS results

Beam	Au	Au	Au	Au	Au	Au	Pb	Pb
Energy (MeV)	0.5	1	2.4	3.5	5.5	10	250	850
Range (μm) ^a	0.15	0.25	0.56	0.81	1.3	2.2	16	40
Total dE/dx (keV/nm) ^a	4.23	4.3	4.3	4.3	4.5	4.8	22.2	28.1
Nuclear dE/dx (keV/nm) ^a	3.3	3.1	2.4	2.1	1.7	1.2	0.15	0.06
Avrami exponent ^b	3.5	3.7	2.5	2.0	1.35	1	1	1
Nuclear cross-section σ_n (10^{-14} cm^2)	23.5	19	(16) ^c	(14) ^c	(12) ^c	(8) ^c	—	—
Electronic dE/dx (keV/nm) ^a	0.93	1.2	1.9	2.2	2.8	3.6	22	28
Electronic cross-section σ_e (10^{-14} cm^2)	—	—	0.95	1.2	5.9	6.6	109	105
Mean dE/dx (keV/nm) ^d				4.3	4.2	4.5	15.6	21.3

Ramos, NIMB (2000)

Ion track analysis using RBS/channeling

Core-halo ion track structure

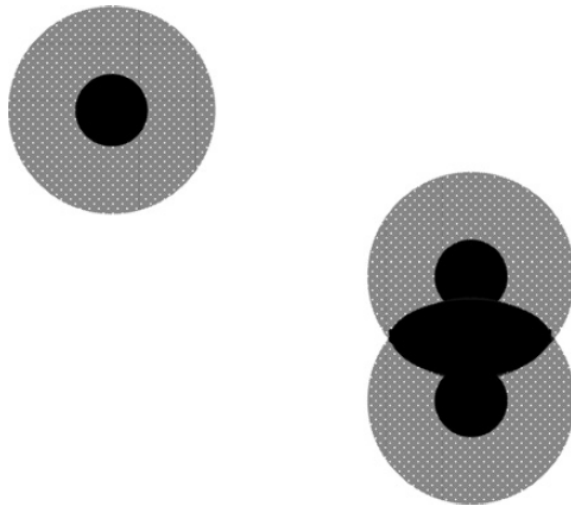


Fig. 3. Schematics of the physical process underlying the multi-impact model, with $N = 2$. Amorphized areas (one core or two halo impacts) are shown in black, whereas pre-amorphized areas (one halo impact) are shown in grey.

Garcia et al., NIMB (2011)

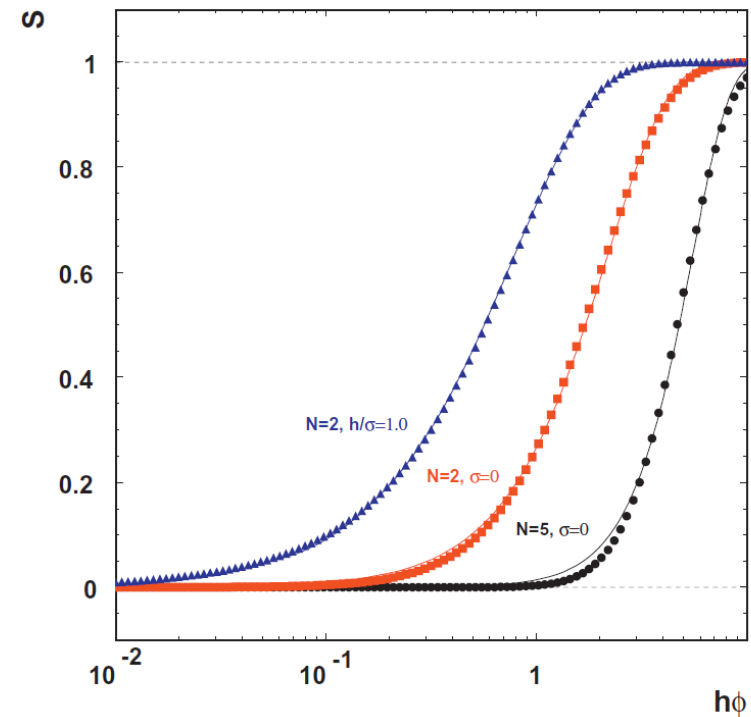
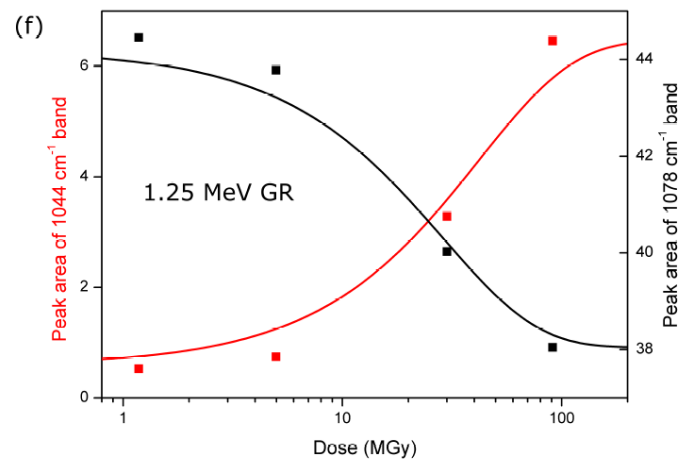
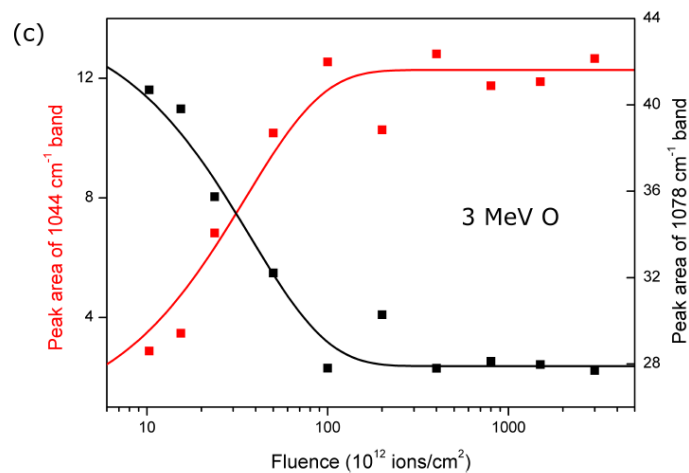
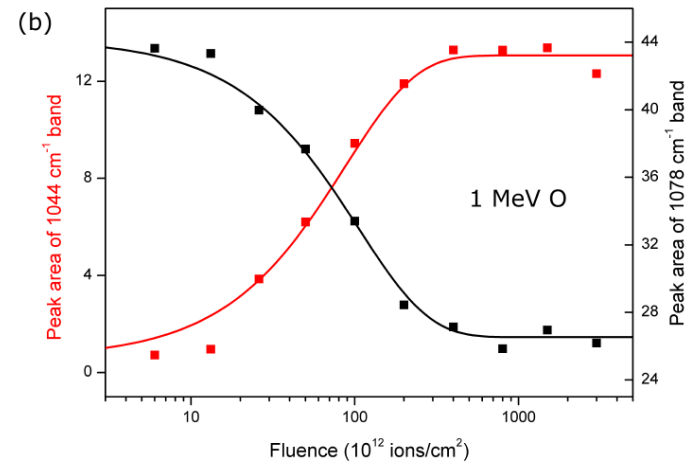
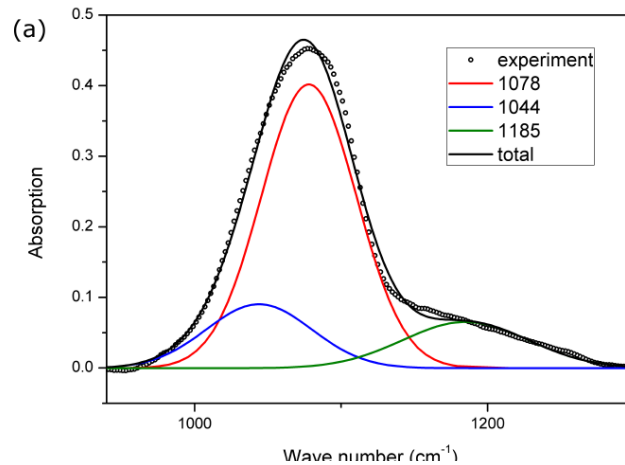


Fig. 6. Fractional amorphized area S , calculated according to the impact-overlapping model with the values indicated in the graph for the parameters N , σ , as a function of the fluence normalized to the inverse area of a halo h (black circles $N = 5$, $\sigma = 0$; red squares $N = 2$, $\sigma = 0$; blue triangles $N = 2$, $\sigma = h$). The solid lines show the result of an Avrami fit to each of these three cases. (For interpretation of the

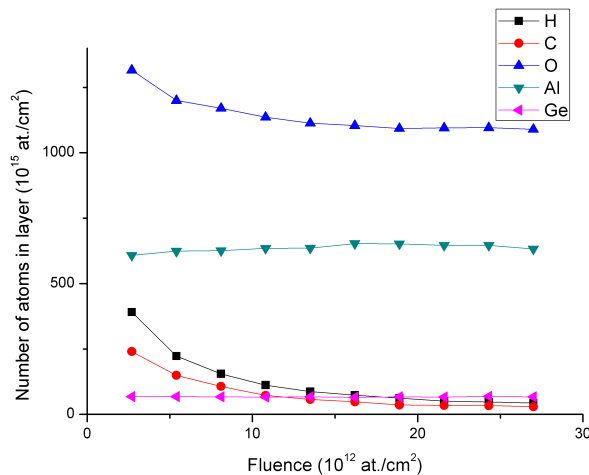
Ion track analysis using other techniques

IR spectroscopy of ion tracks in a-SiO₂

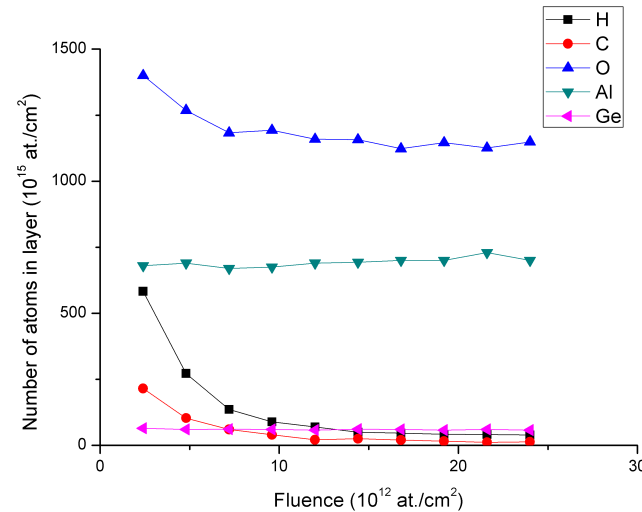


Ion track analysis using other techniques

ToF ERDA of hydrogen loss from Al_2O_3 film



16 MeV I, $\Theta = 20^\circ$



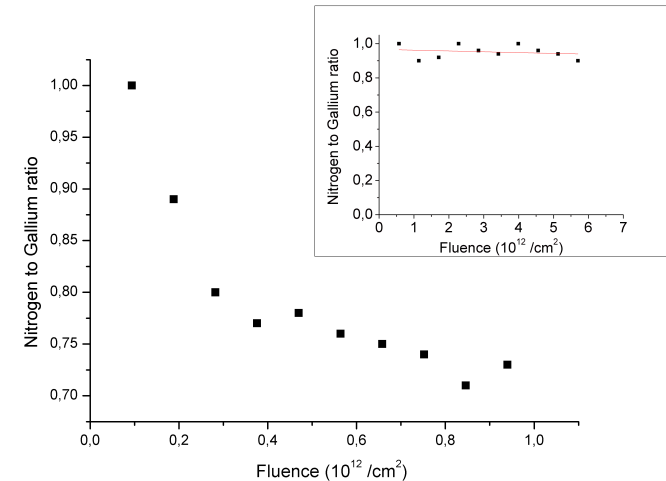
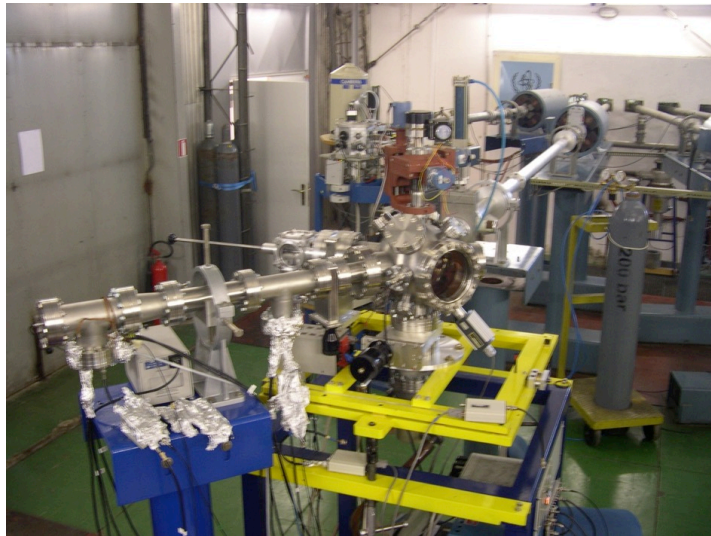
23 MeV I, $\Theta = 20^\circ$

Ion track radius 1-2 nm, 20% bigger for higher energy

M. Karlusic et al., unpublished

Ion tracks on the surfaces: GaN, TiO₂

In situ grazing incidence ToF-ERDA



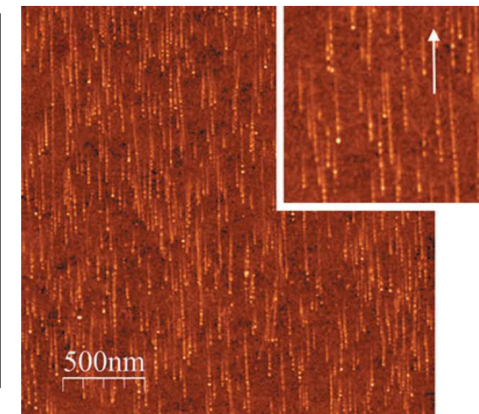
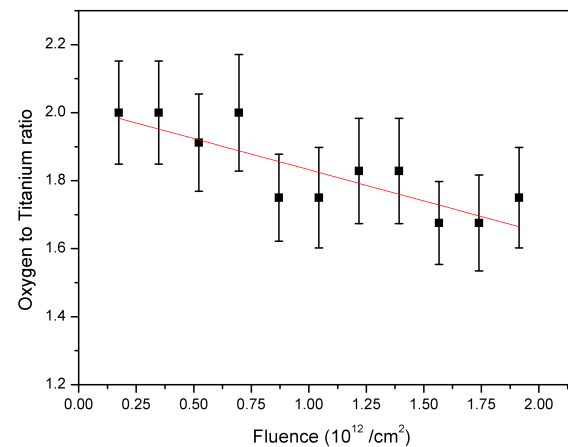
GaN: J. Phys. D: Appl. Phys. (2015)

SrTiO₃, SiO₂, muscovite mica:
Materials (2017)

CaF₂: New J. Phys. (2017)

MgO, Al₂O₃, MgAl₂O₄:
unpublished

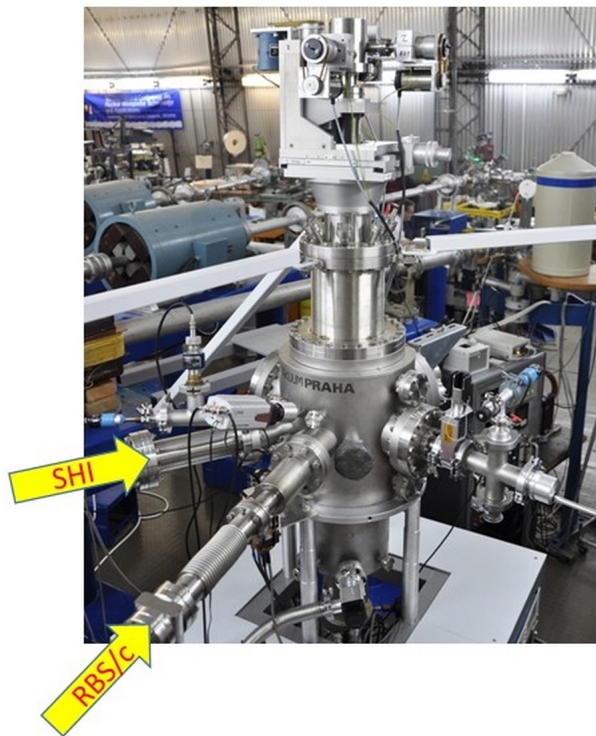
TiO₂: J. Appl. Cryst. (2016)



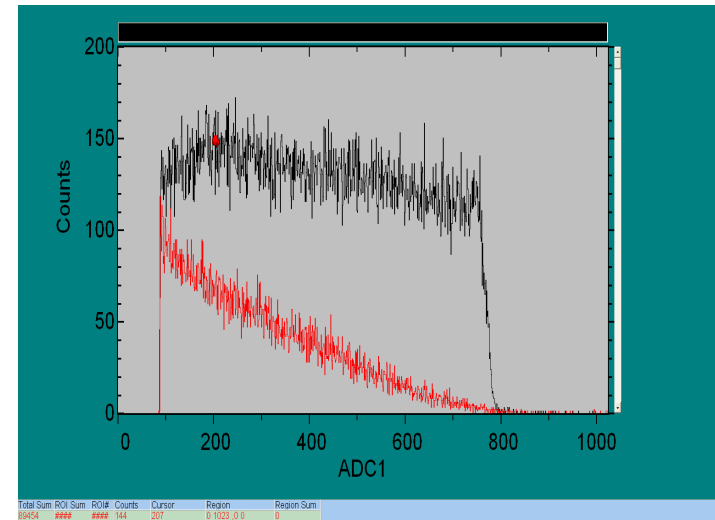
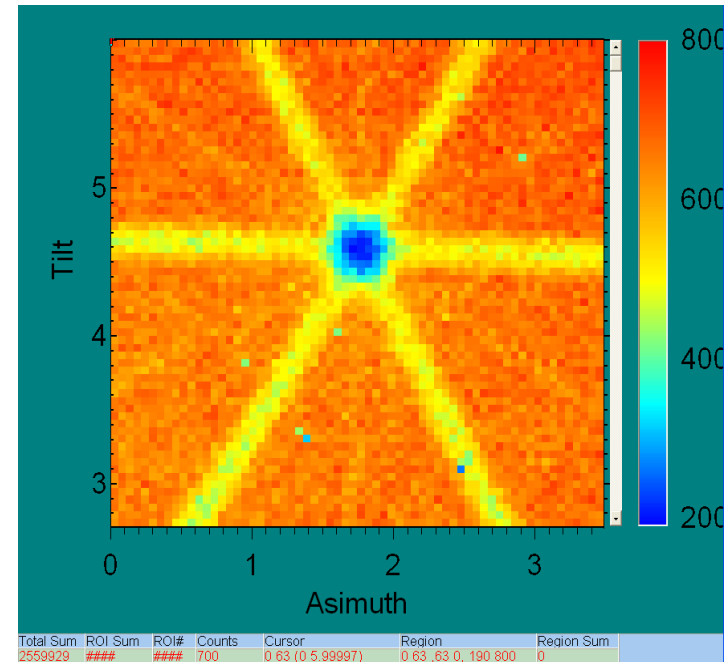
Overview

1. Introduction to IBA
2. RBS/channeling for ion tracks
3. RBS/c @ RBI

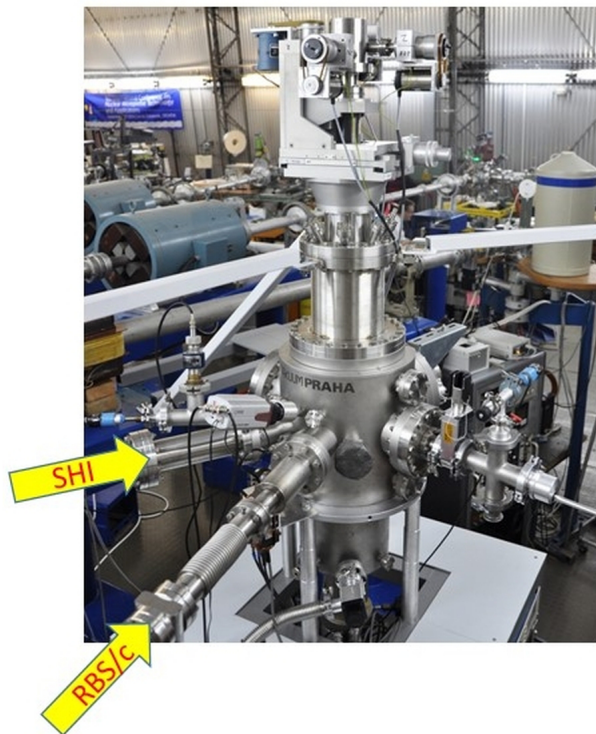
RBS/C @ RBI-AF (DUAL BEAM END STATION)



6 MV Tandem Van de Graaff
1 MV Tandetron

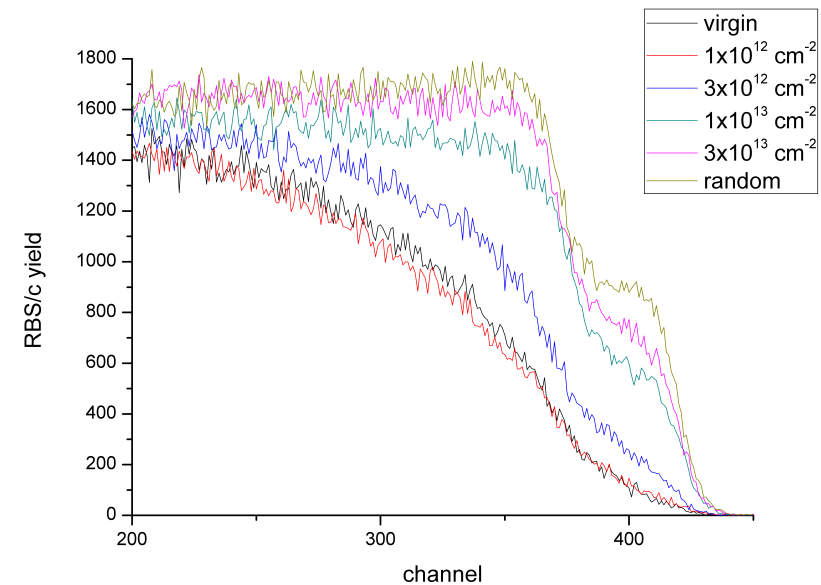


RBS/C @ RBI-AF (DUAL BEAM END STATION)



6 MV Tandem Van de Graaff
1 MV Tandetron

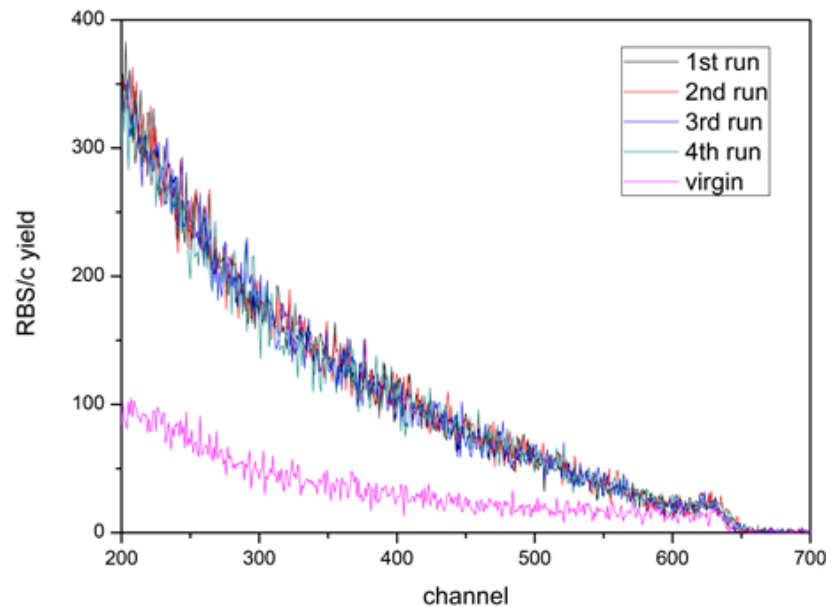
In situ RBS/c



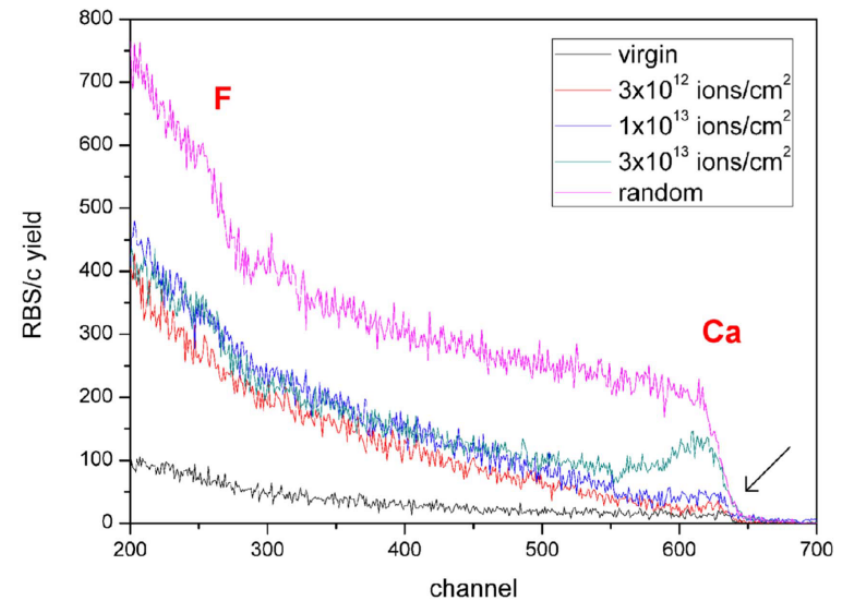
5 MeV Si \Rightarrow SiO₂ quartz
RBS/c: 1 MeV protons

*M. Karlusic et al.,
Materials (2018)*

RBS/C @ RBI-AF (DUAL BEAM END STATION)



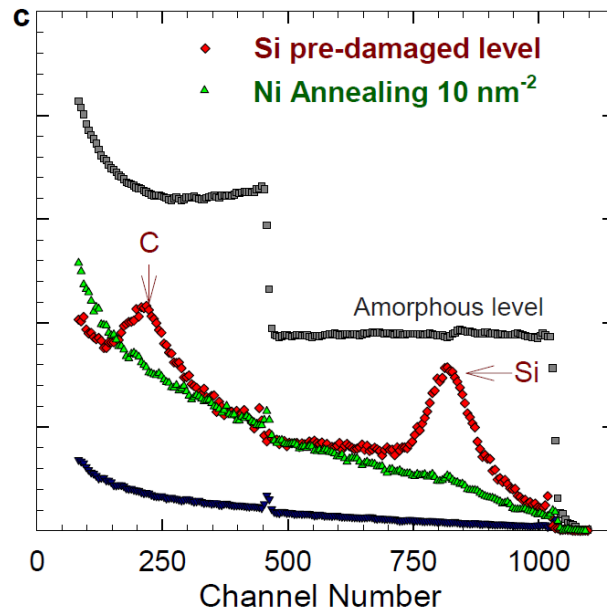
23 MeV I, 3×10^{12} ions/cm²
RBS/c using 2 MeV Li



23 MeV I @ CaF₂
RBS/c: 2 MeV Li

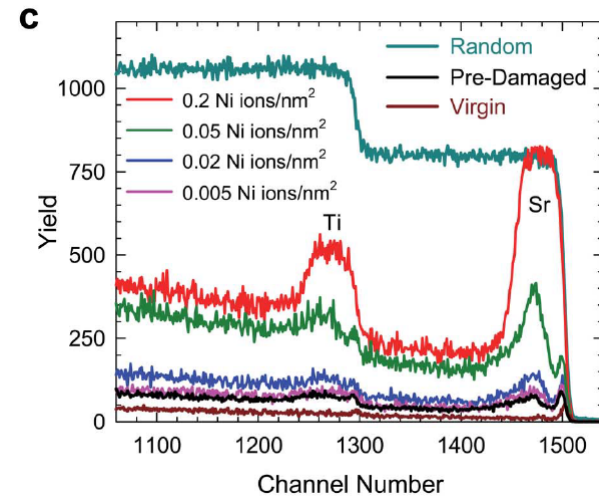
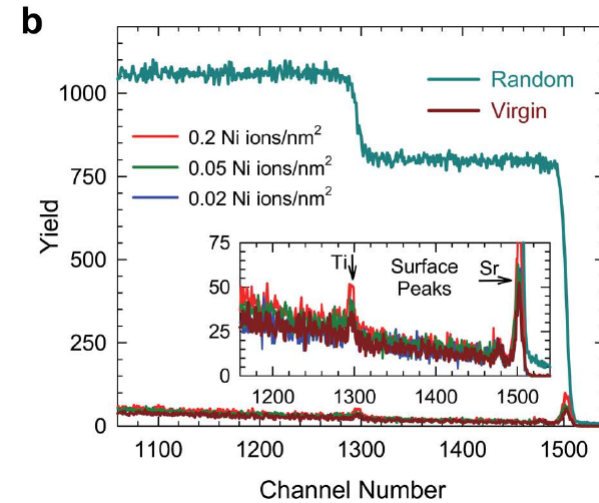
*M. Karlušić et al.,
New J. Phys. (2017)*

SHIBIEC: SiC ANTI-SHIBIEC: SrTiO_3



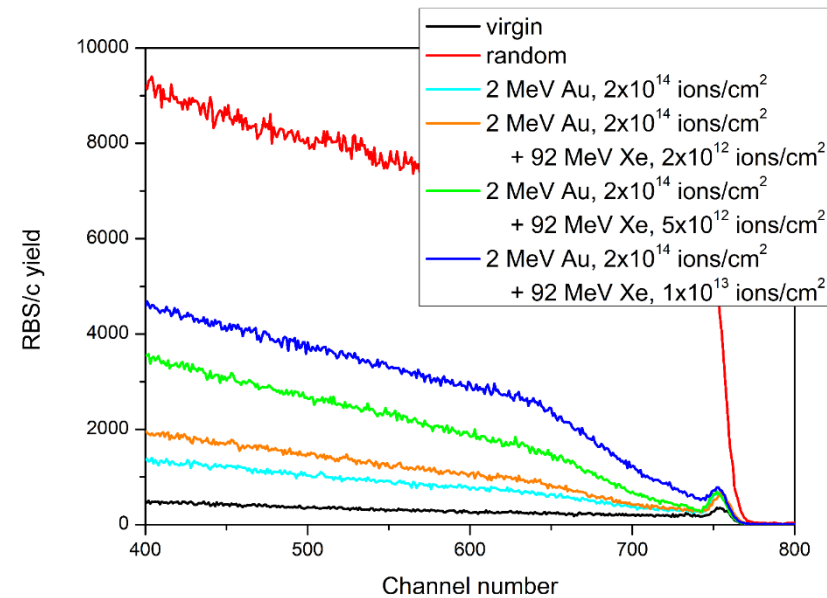
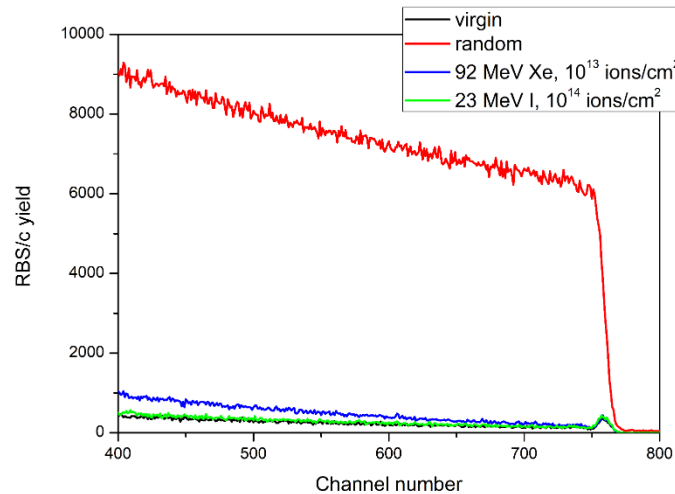
Y. Zhang et al., Nat. Comm. (2015)

*A. Benyagoub et al.,
Appl. Phys. Lett. (2006)*



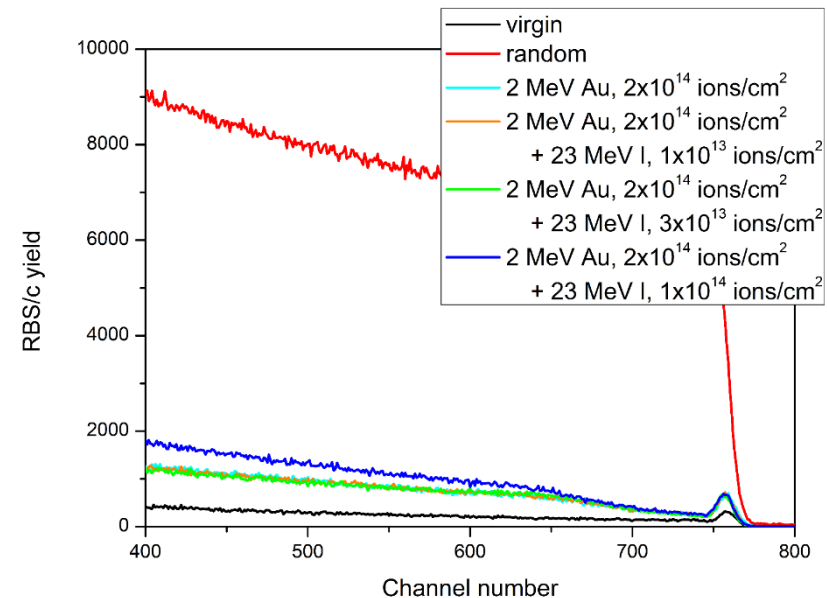
Weber et al., Sci. Rep. (2015)

Ion tracks in PRE-damaged GaN

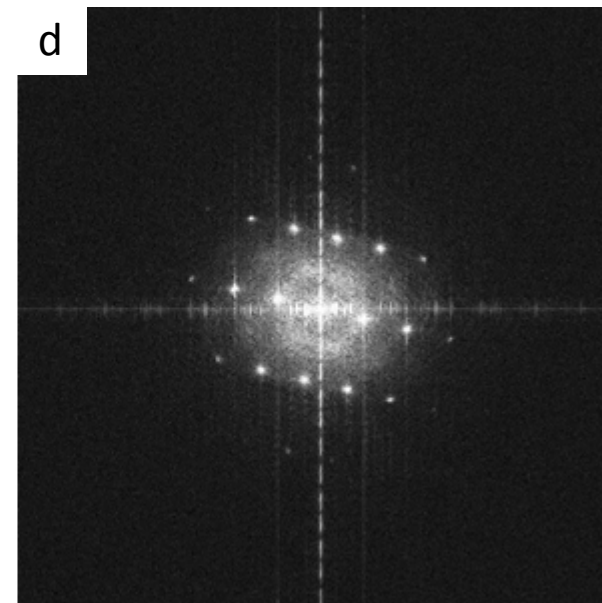
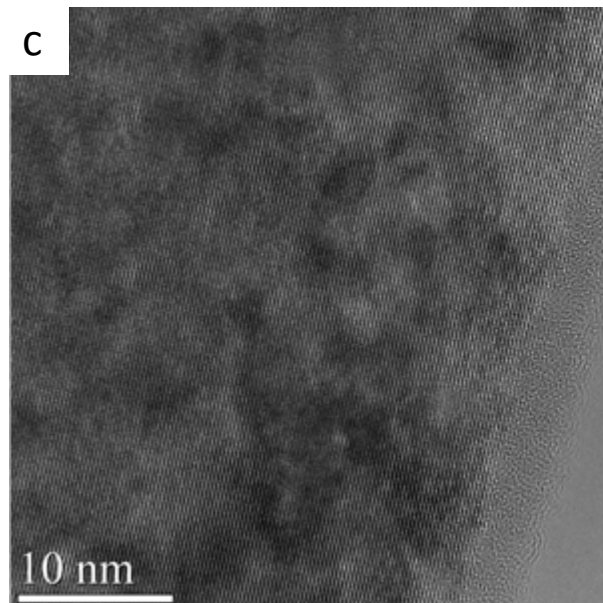
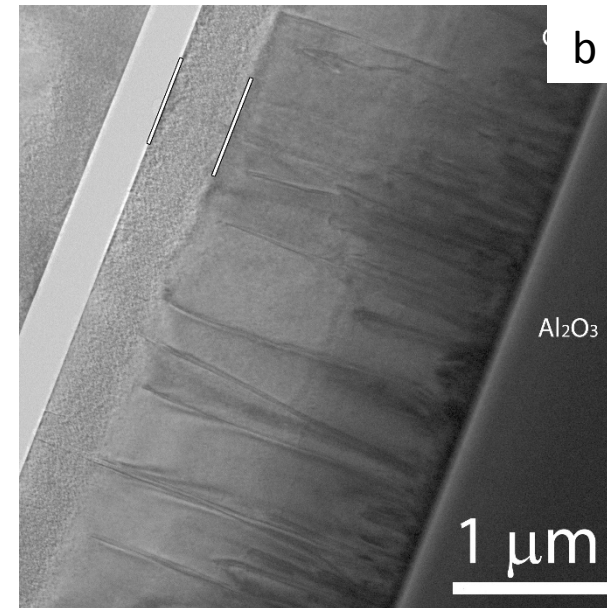
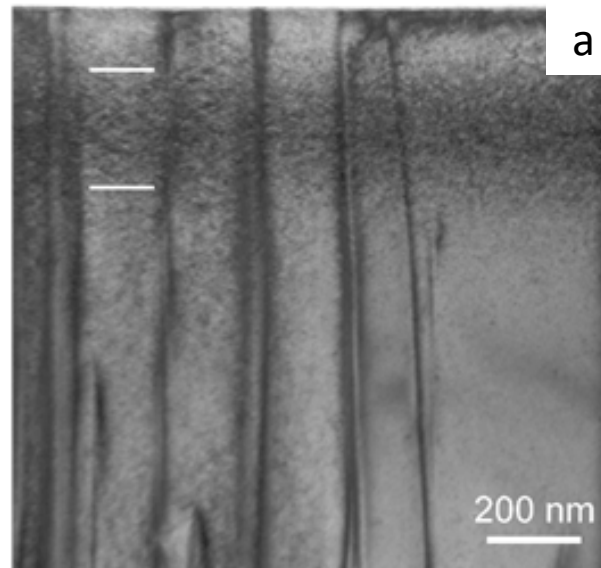
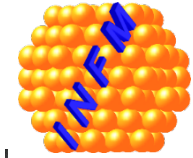


HZDR: 2 MeV Au
GANIL: 90 MeV Xe
RBI: 23 MeV I
HZDR: 1.7 MeV He RBS/c

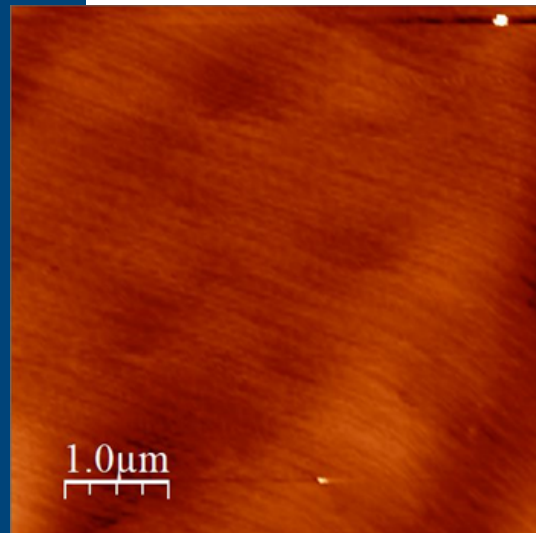
Karlusic et al., unpublished



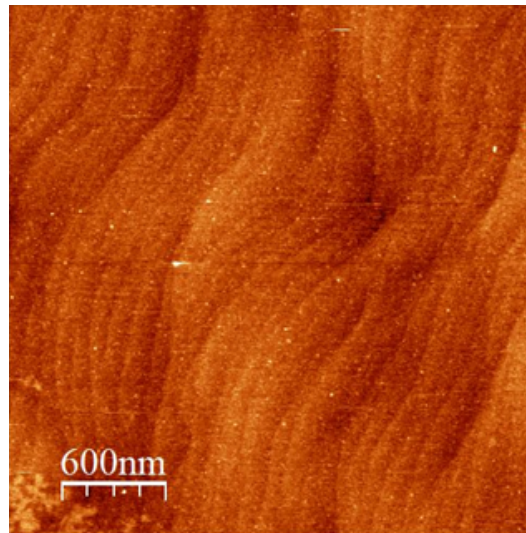
Ion tracks in PRE-damaged GaN



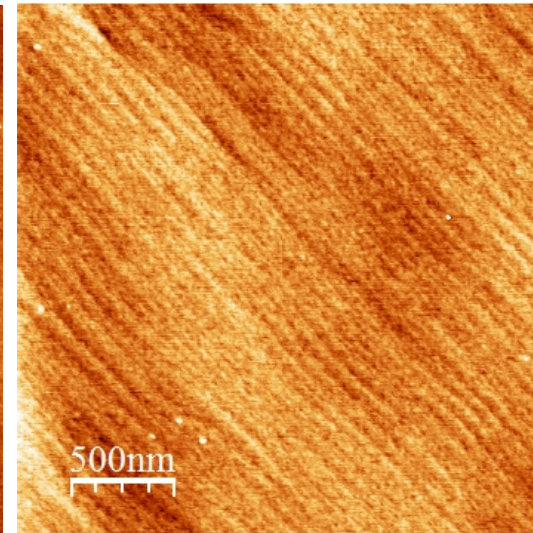
Ion tracks in PRE-damaged GaN



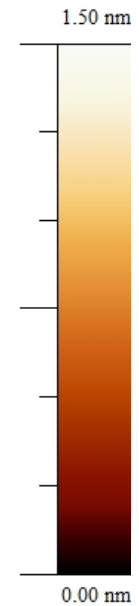
Virgin:
RMS roughness
= 0.27 nm



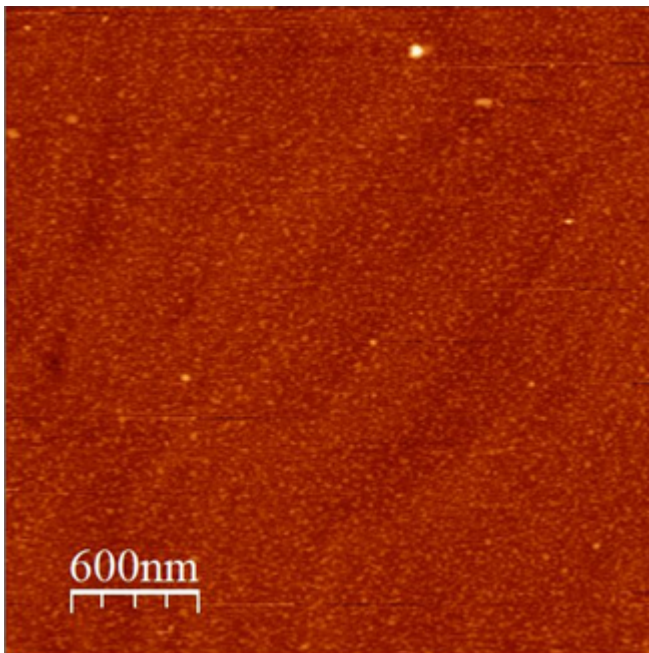
2 MeV Au
(2×10^{14} ions/cm²):
RMS roughness
= 0.39 nm



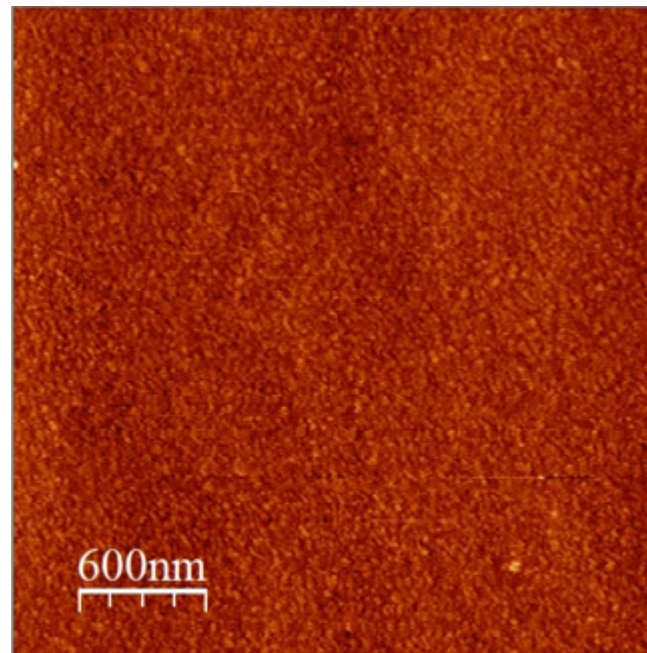
90 MeV Xe
(10^{13} ions/cm²):
RMS roughness
= 0.3 nm



Ion tracks in PRE-damaged GaN



2 MeV Au +
90 MeV Xe
(10¹² ions/cm²):
RMS roughness
= 0.83 nm



2 MeV Au +
90 MeV Xe
(10¹³ ions/cm²):
RMS roughness
= 1.31 nm

SUMMARY

Ion track threshold: depends on dE_e/dx , not E !
Complementary to higher energy accelerator facility
IBA (RBS/C, ERDA) available for track measurements
Higher fluences can be achieved (simulate n , γ)

RBS/c - used for structural analysis of single crystals
Avrami model useful for distinguishing nuclear and
electronic stopping damage
Avrami model also useful for other techniques